

Accelerating scale-up of quantum processors with split accumulation gate quantum dots

Thesis defense

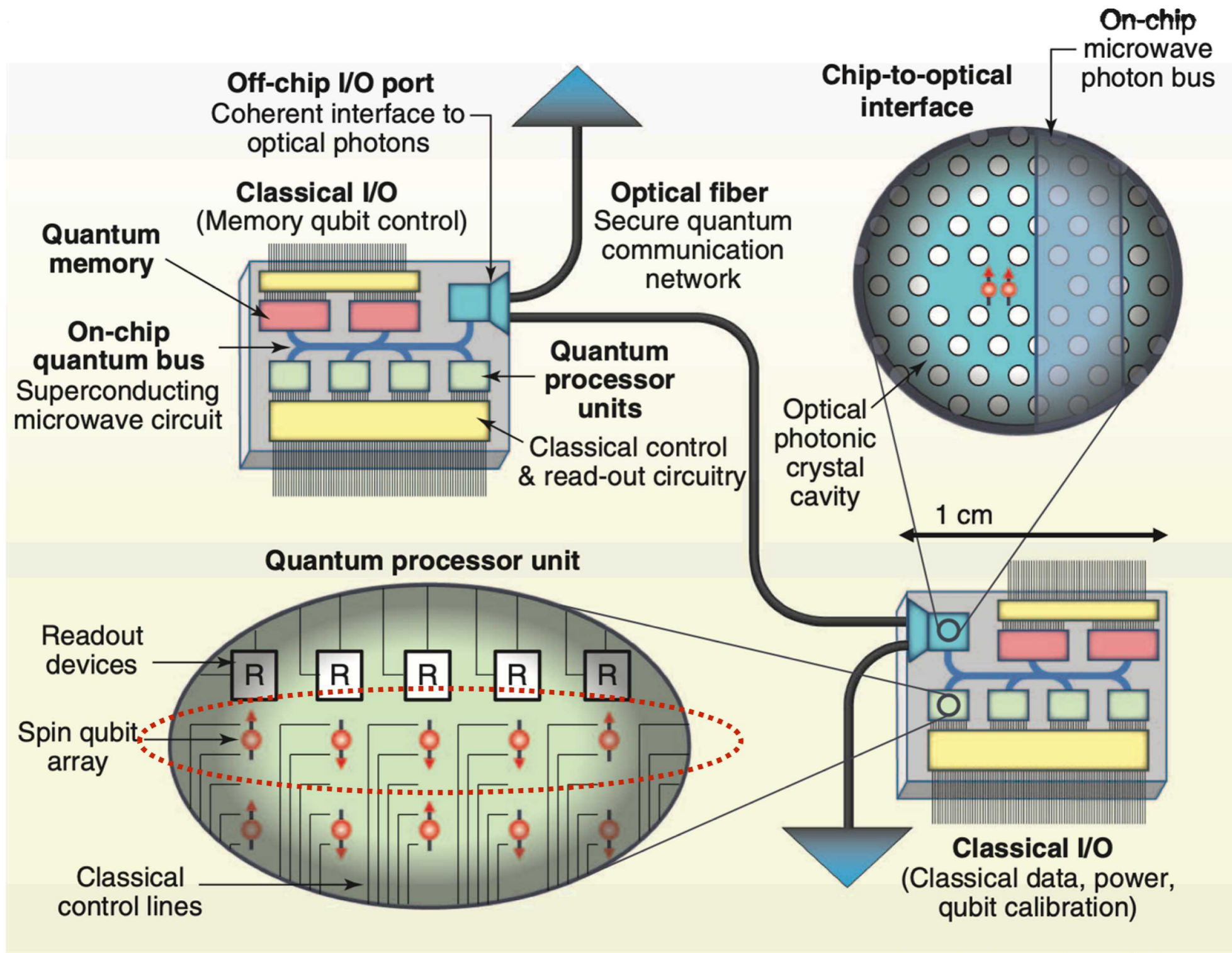
Sophie Rochette

May 15th 2020

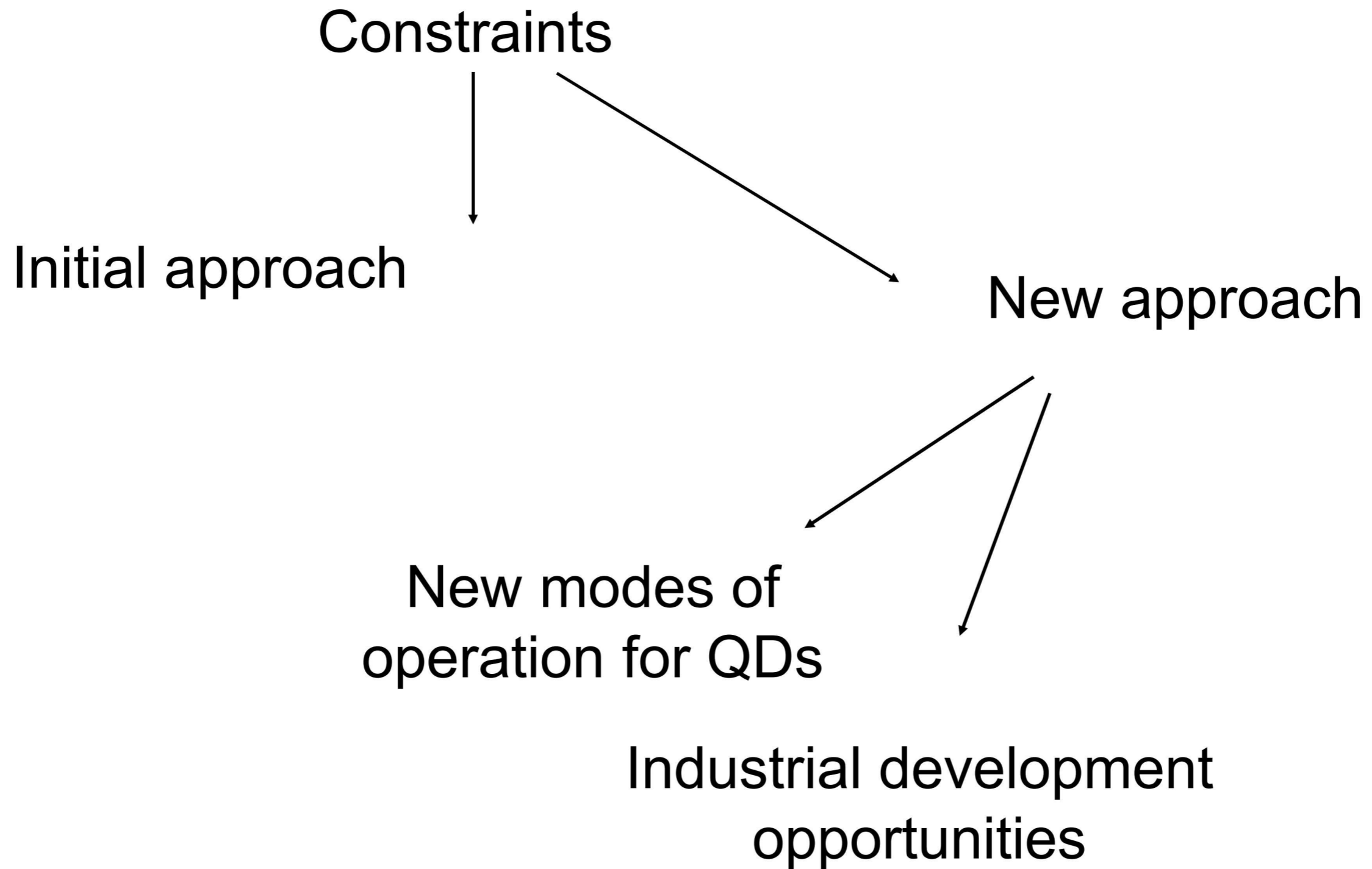


Motivation

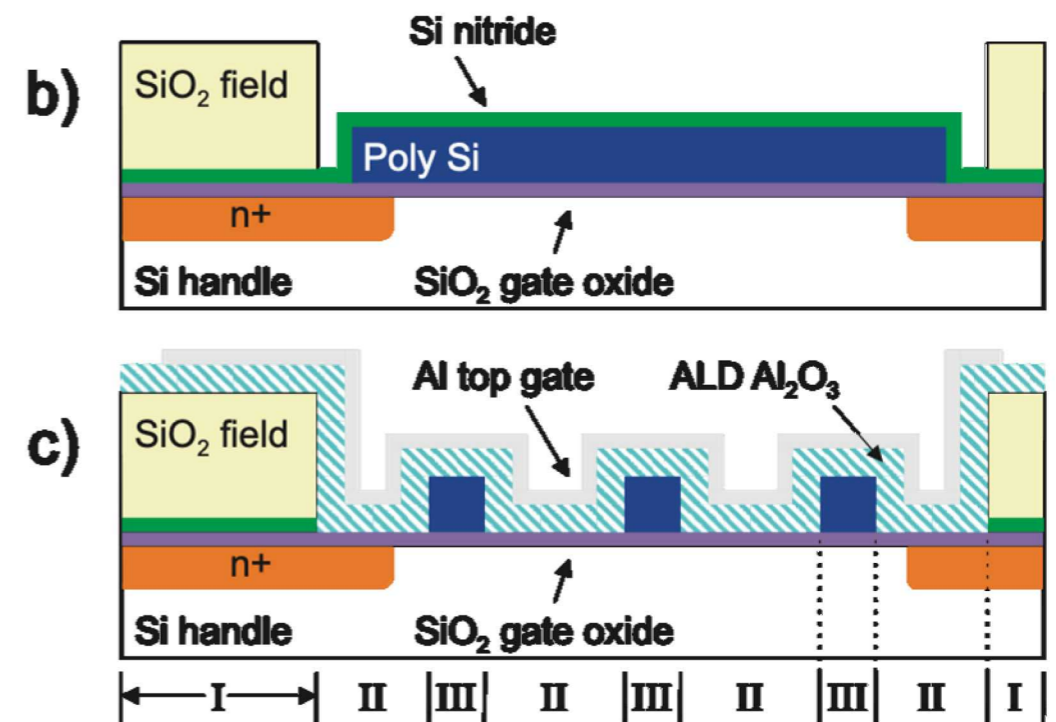
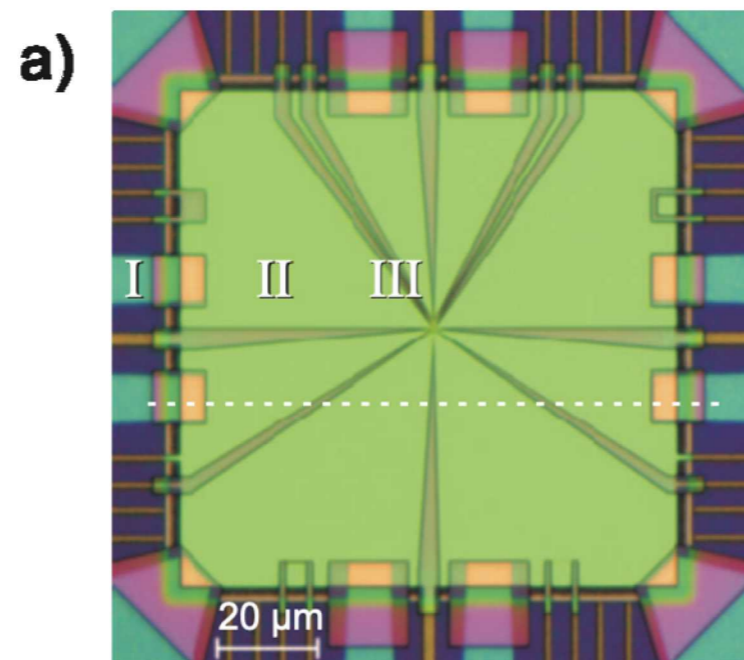
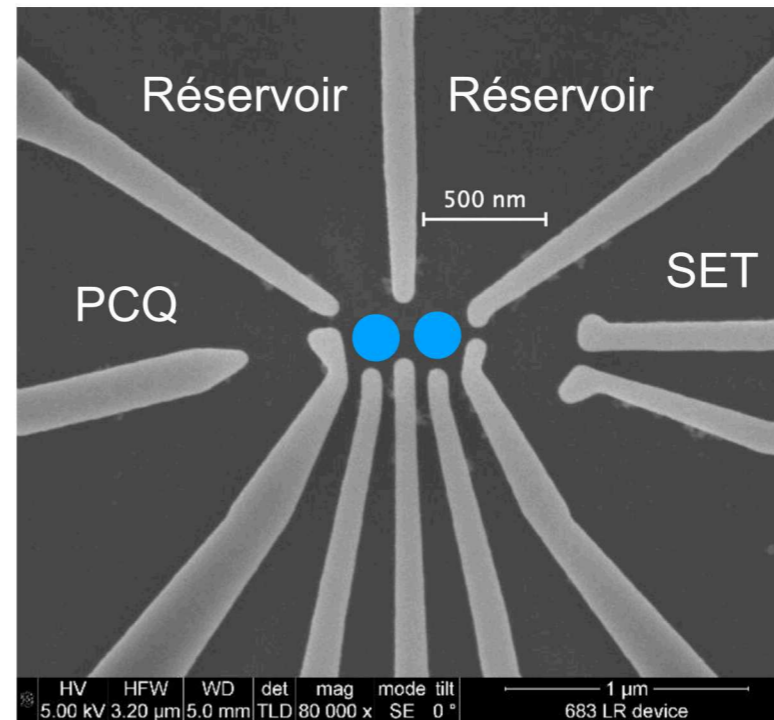
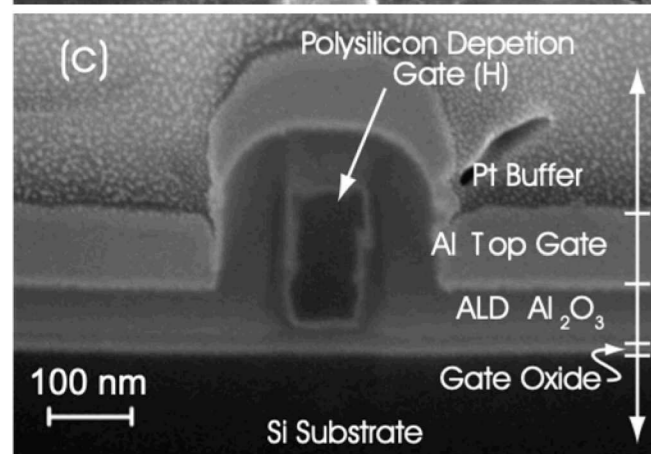
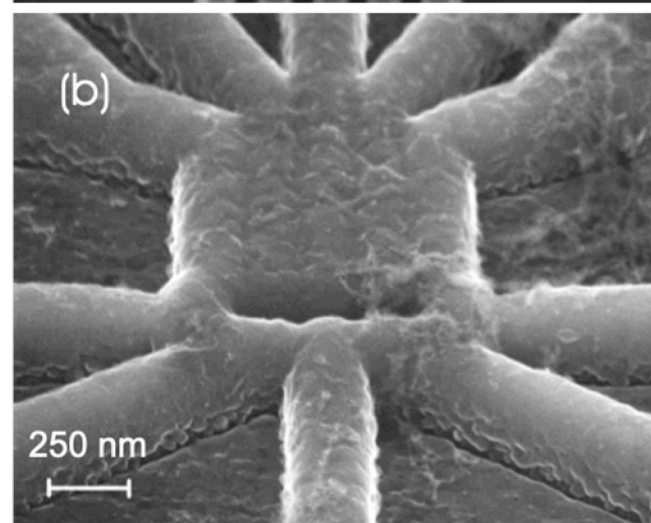
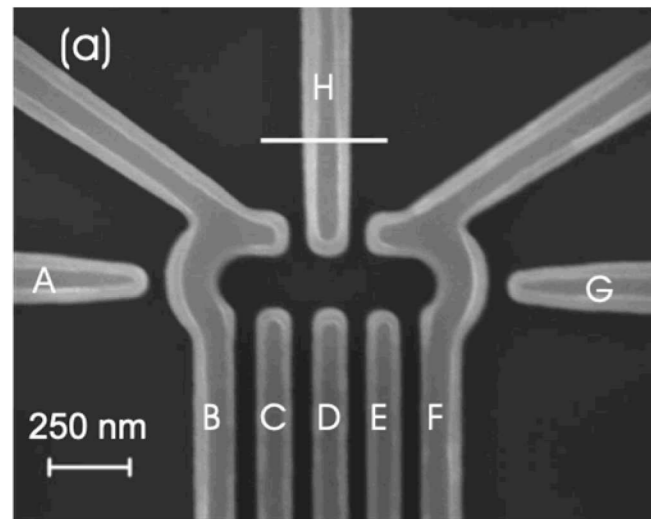
Next step for spin qubits: large-scale integration



Thesis overview

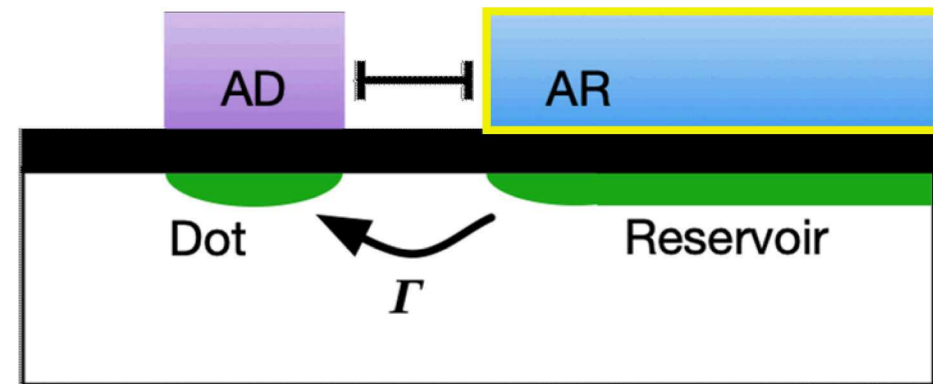
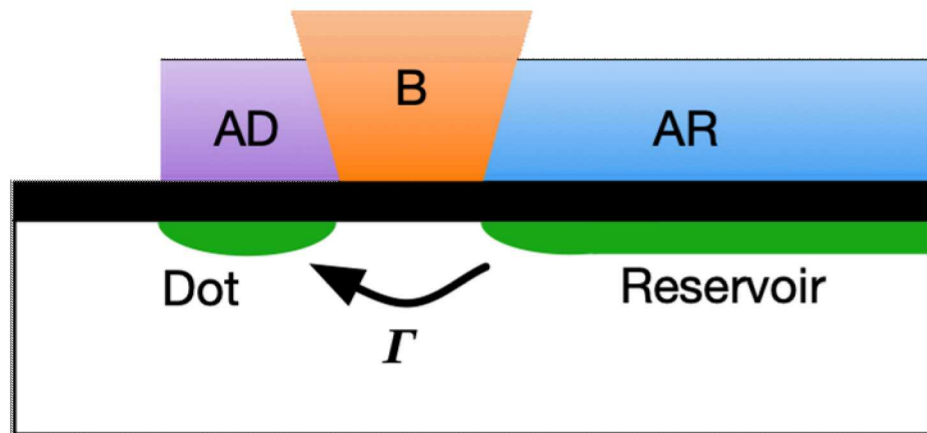


Previous structure: Multi-layers with global accumulation



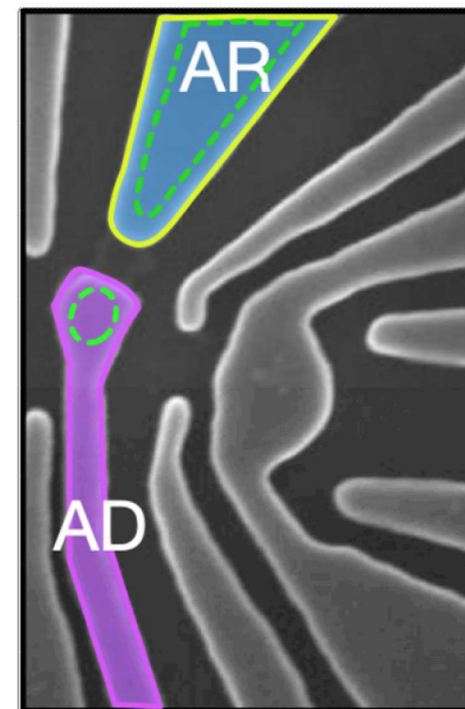
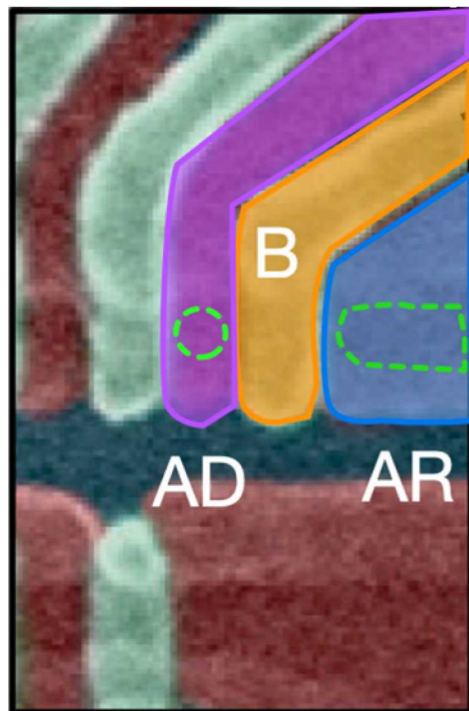
BQ-reservoir tunnel barrier control methods

Local accumulation gates devices



Dedicated barrier gate

No dedicated barrier gate



Objectives:

- Verify respect of minimal performance criterias for qubits;
- Demonstrate possible advantages of the split accumulation gate structure;
- Study particularities of the structure and develop new tools and models.

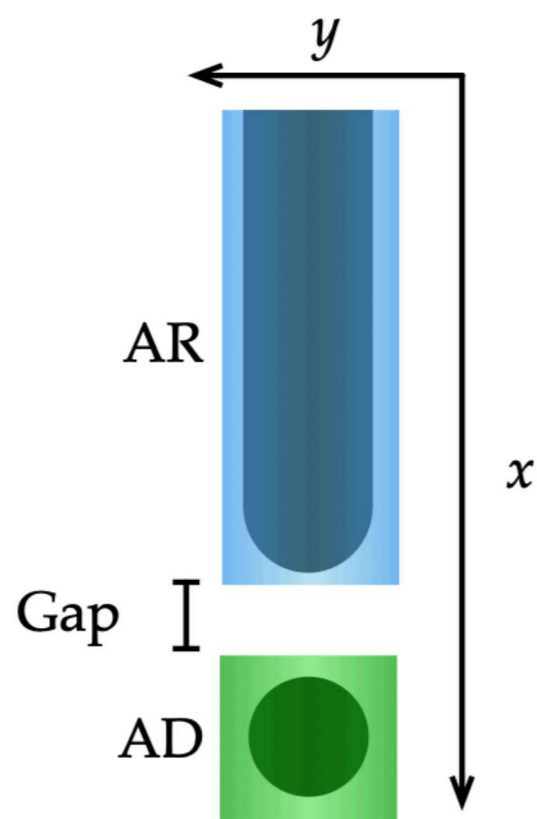
Structure of the talk

1. Elementary notions of quantum dots
2. Split accumulation gate devices
3. Single-electron regime and confinement
4. Control of the tunnel rate with the split accumulation gate structure
5. Role of the reservoir charge density in the split accumulation gate structure operation
6. Scaling: industrial approach
7. Conclusion

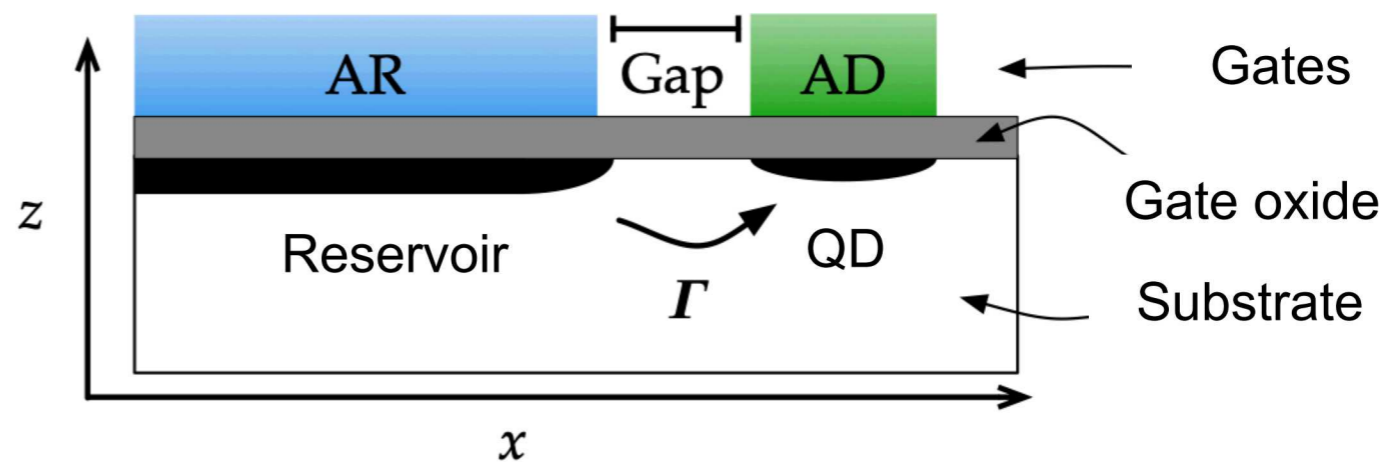
Split accumulation gate devices

Split accumulation gate structure

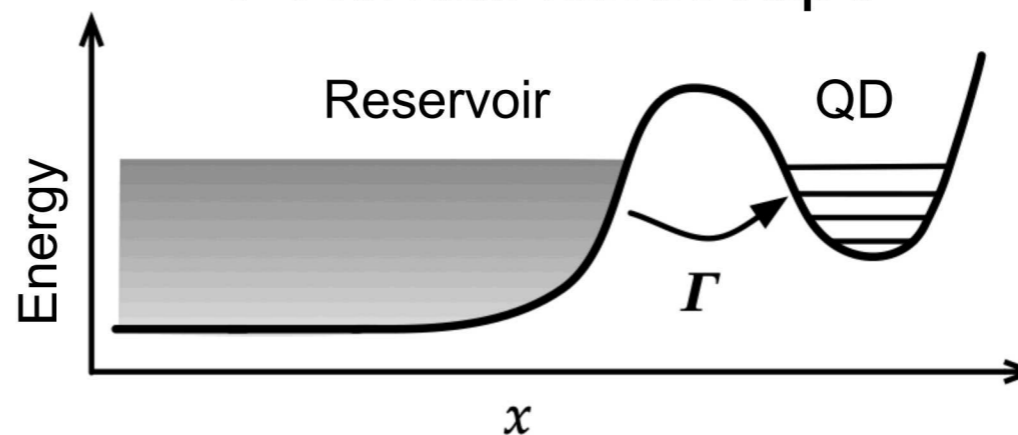
a) Top view



b) Lateral view

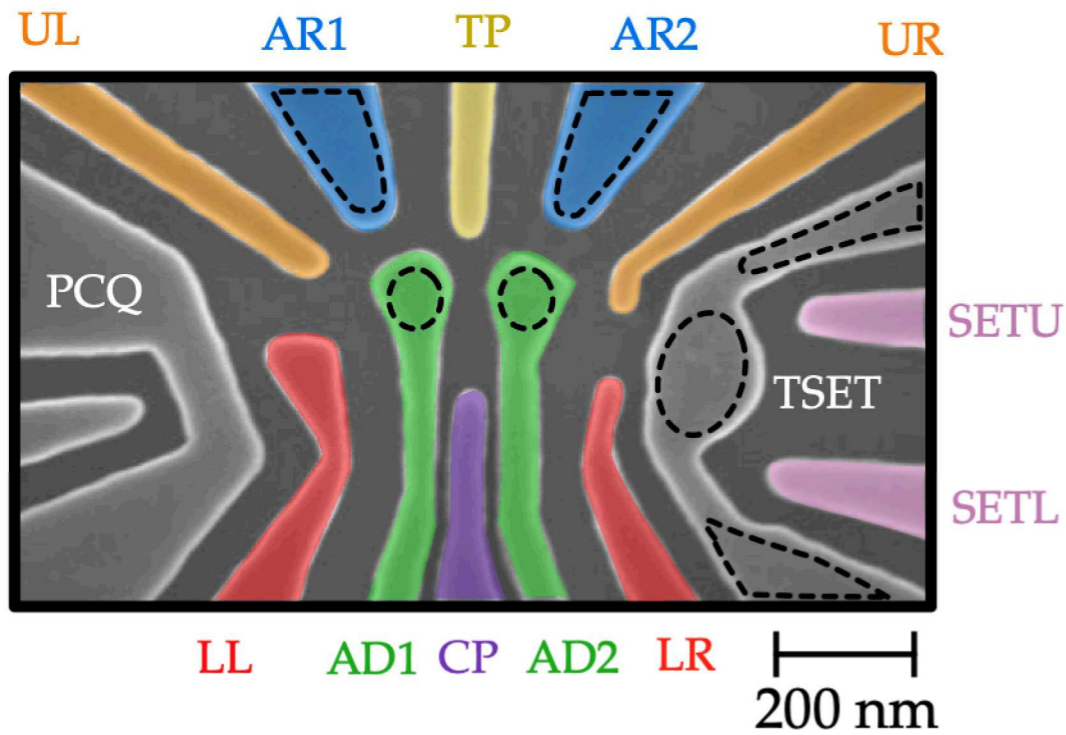


c) Potential landscape

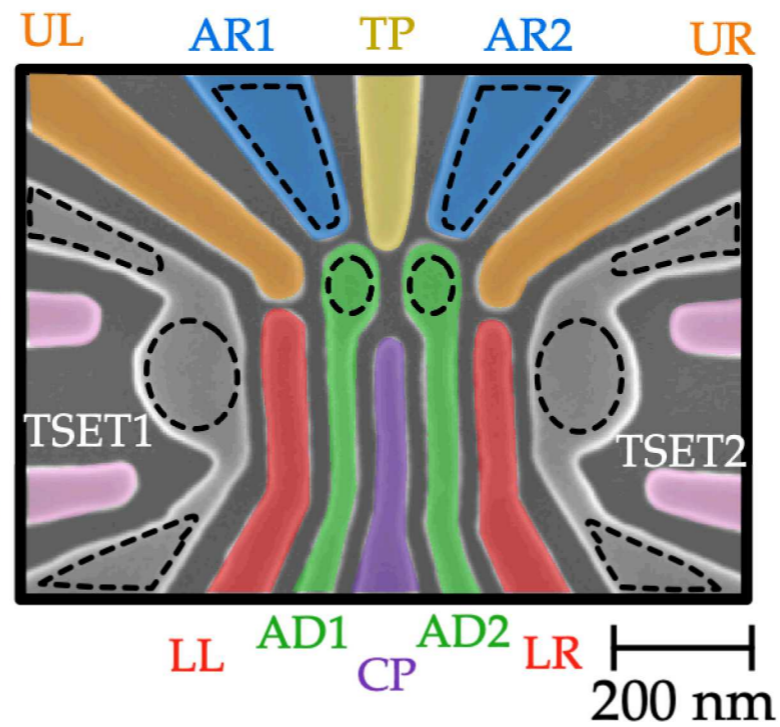


Devices

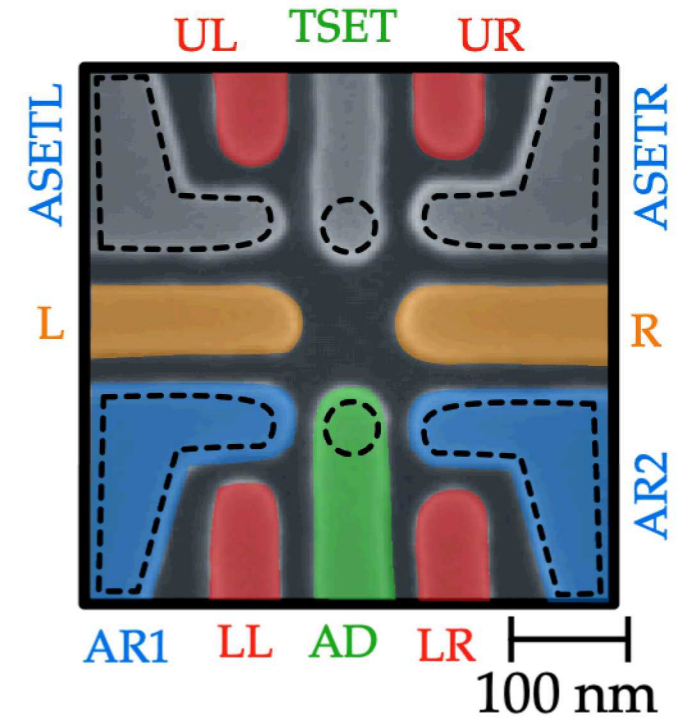
A1 device



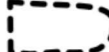







A2 device



B device

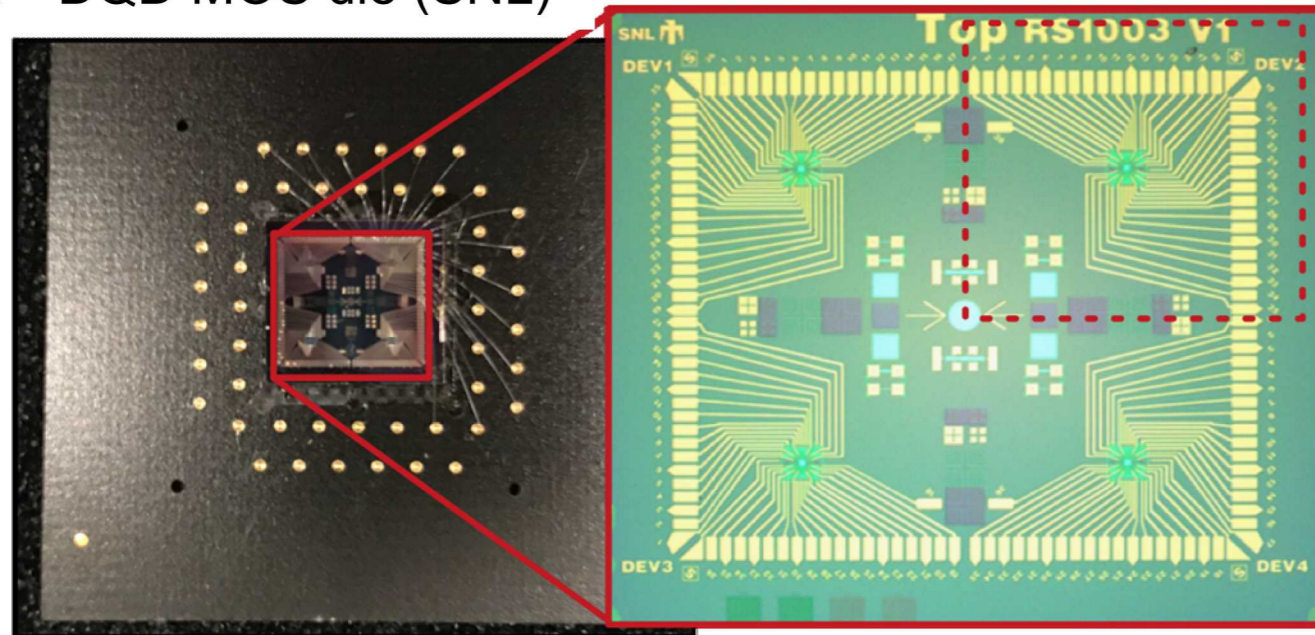


-  Reservoir accumulation gate
-  Quantum dot accumulation gate
-  Accumulated electrons
-  SET control gate

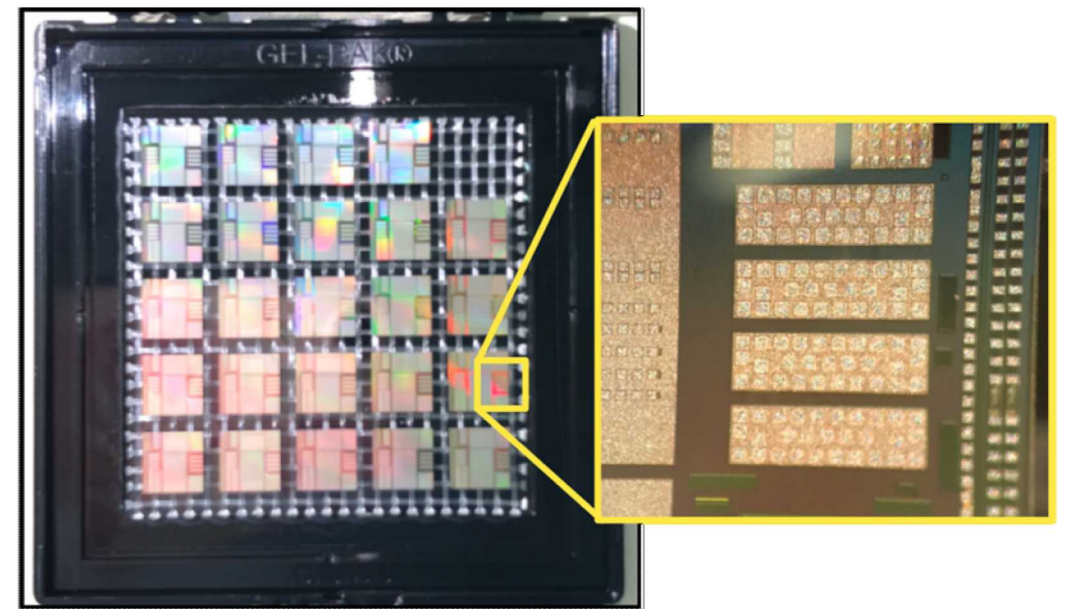
-  Lateral depletion gates
-  Inter-QD coupling and depletion gate
-  Separation gate
-  Inter-QD coupling and depletion gate

Devices

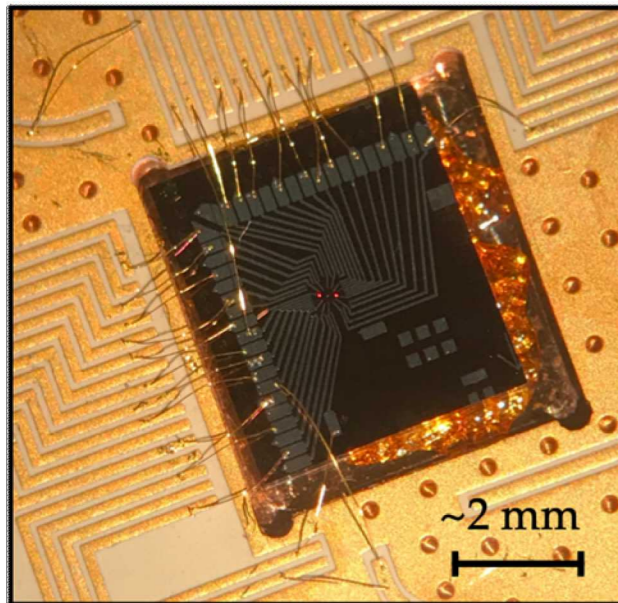
a) DQD MOS die (SNL)



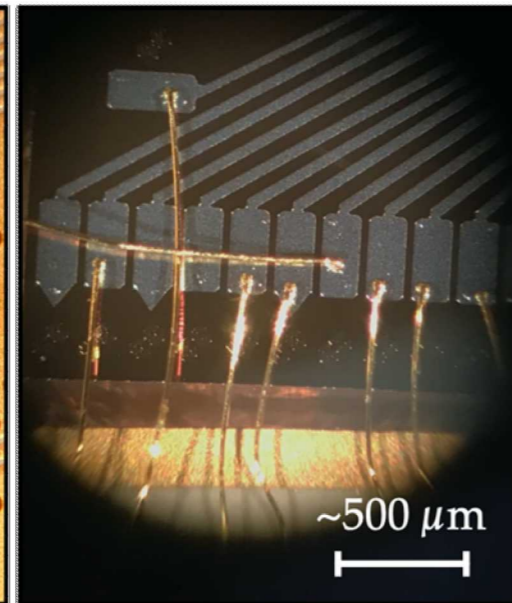
b) 2D FDSOI arrays die (STMicro)



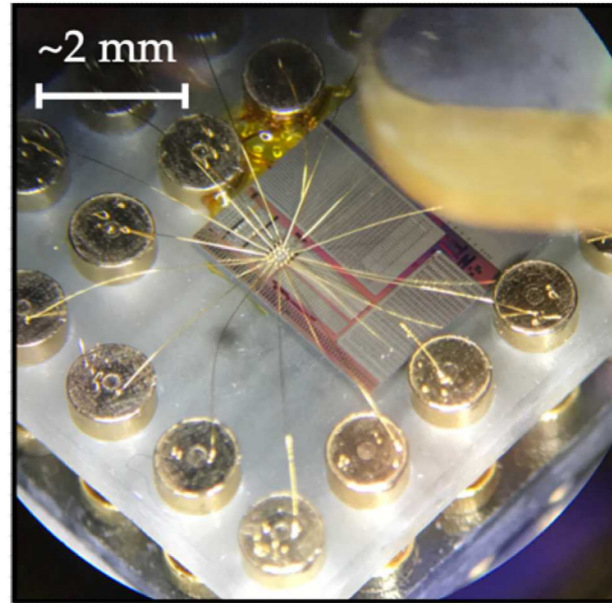
a)



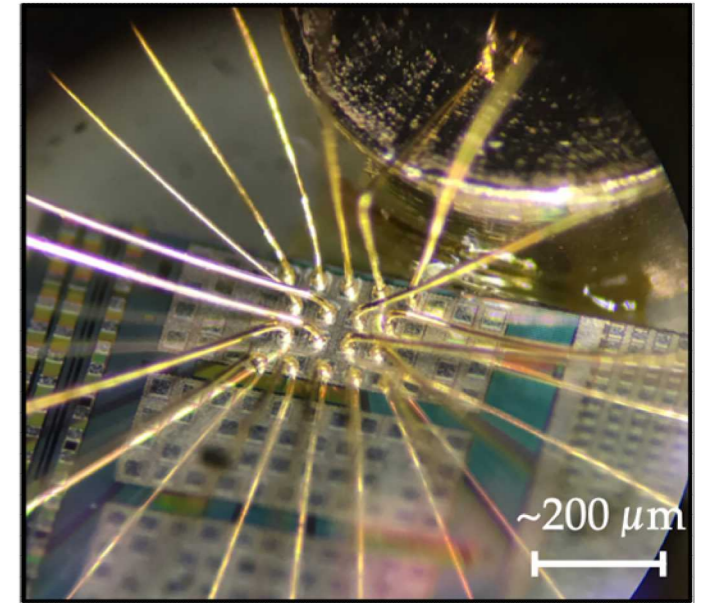
b)



c)



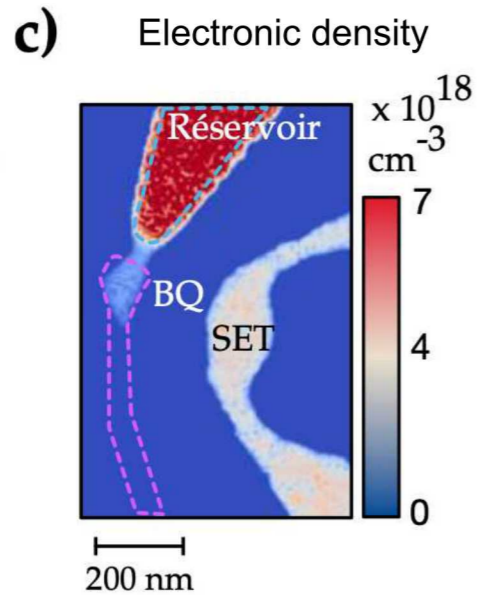
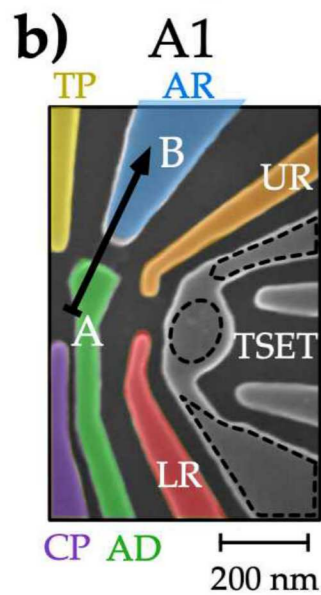
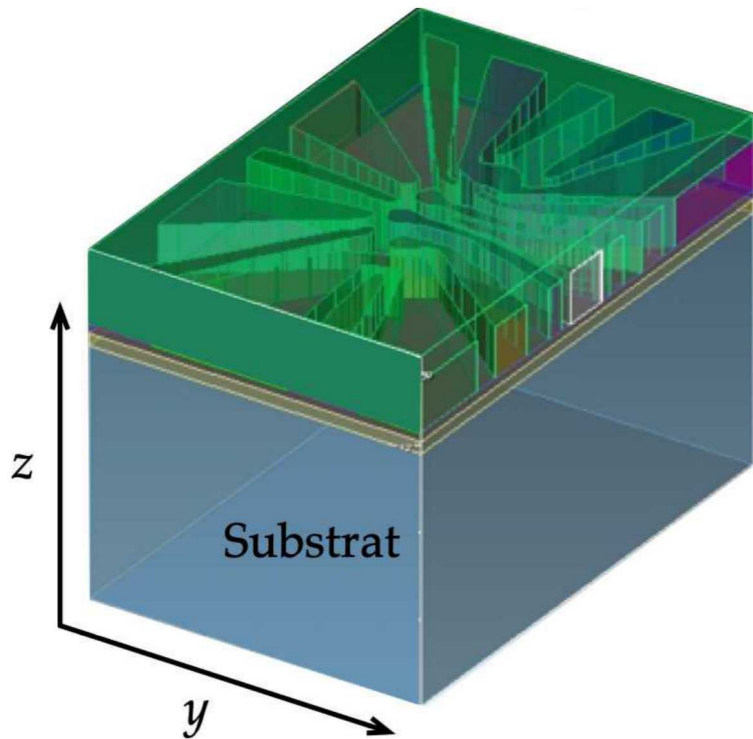
d)



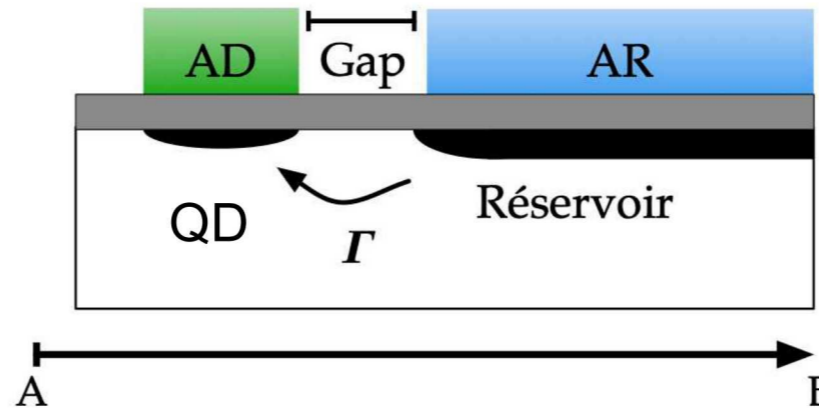
Single electron regime and confinement

Device operation

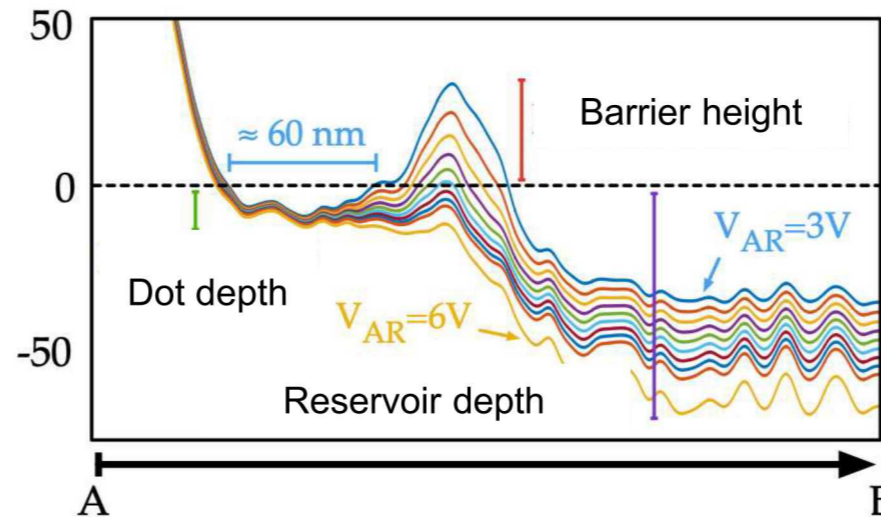
a) QCAD structure, A1 device



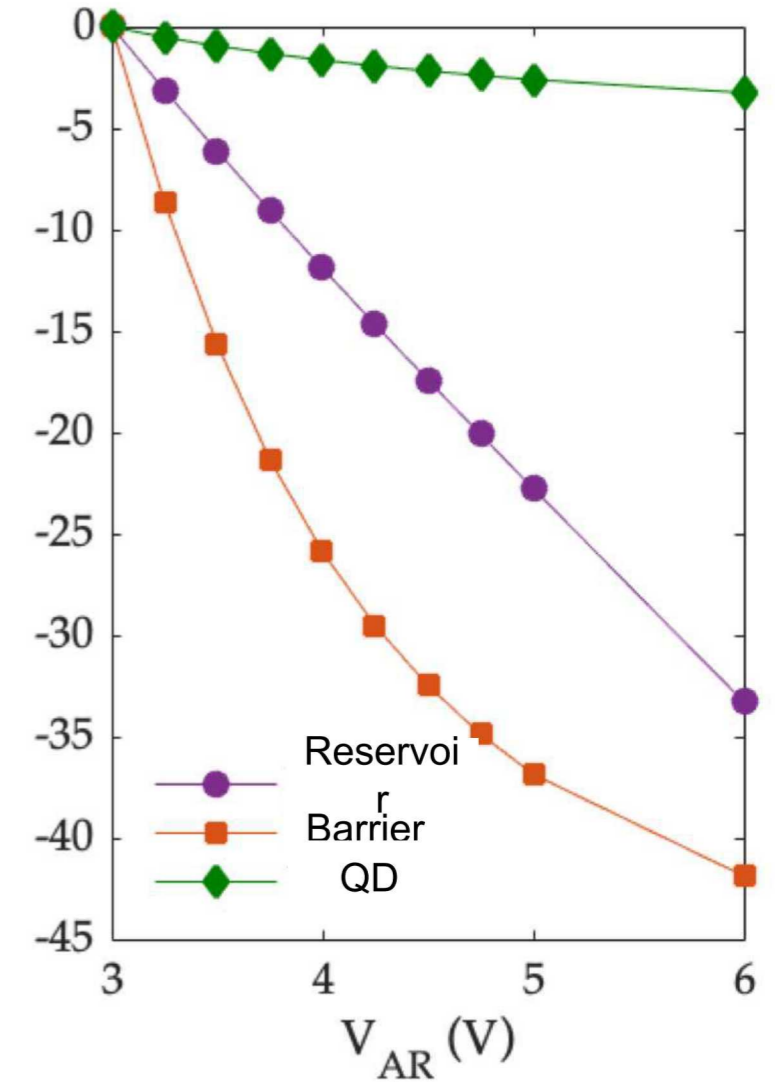
d) Lateral cut



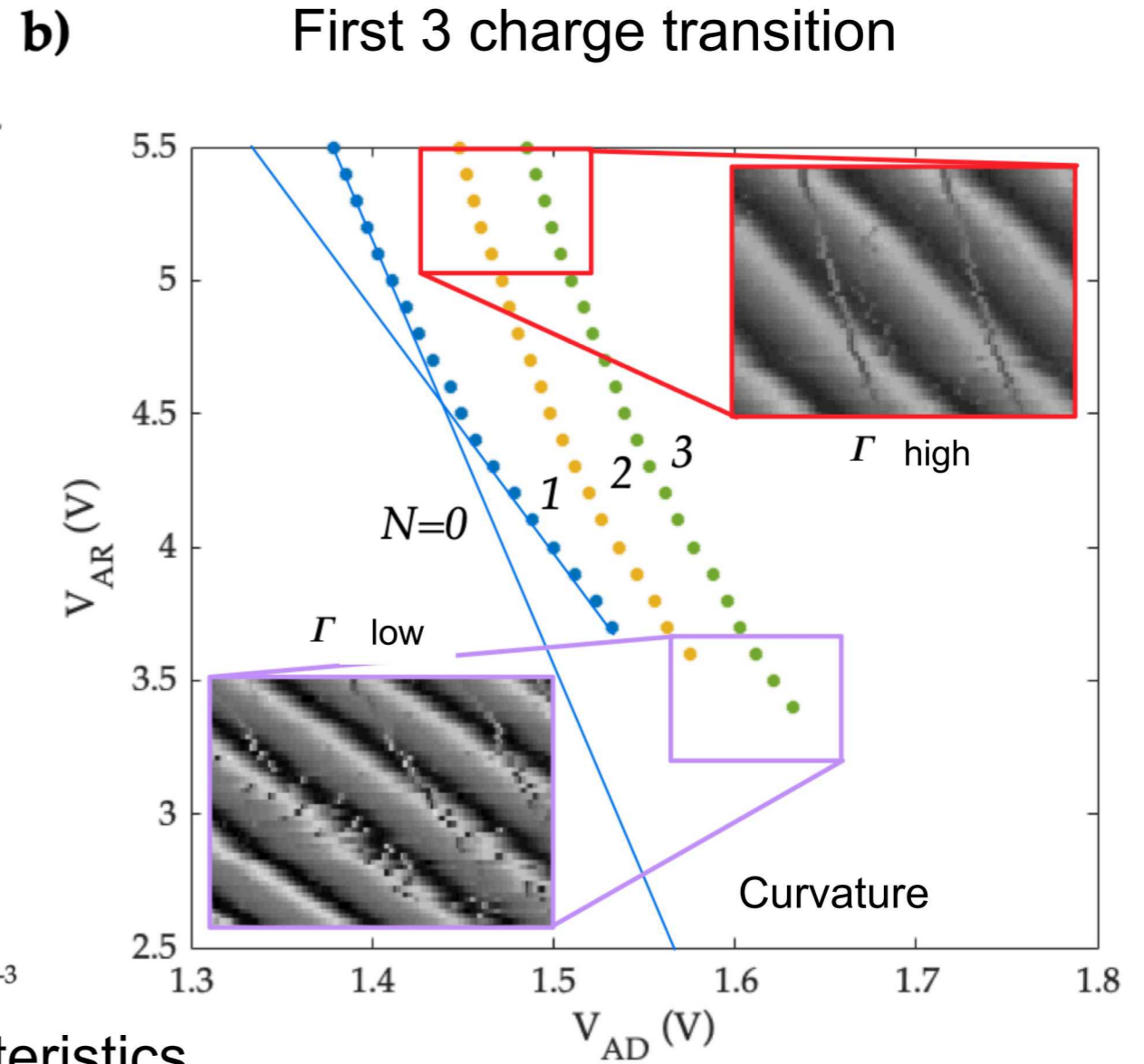
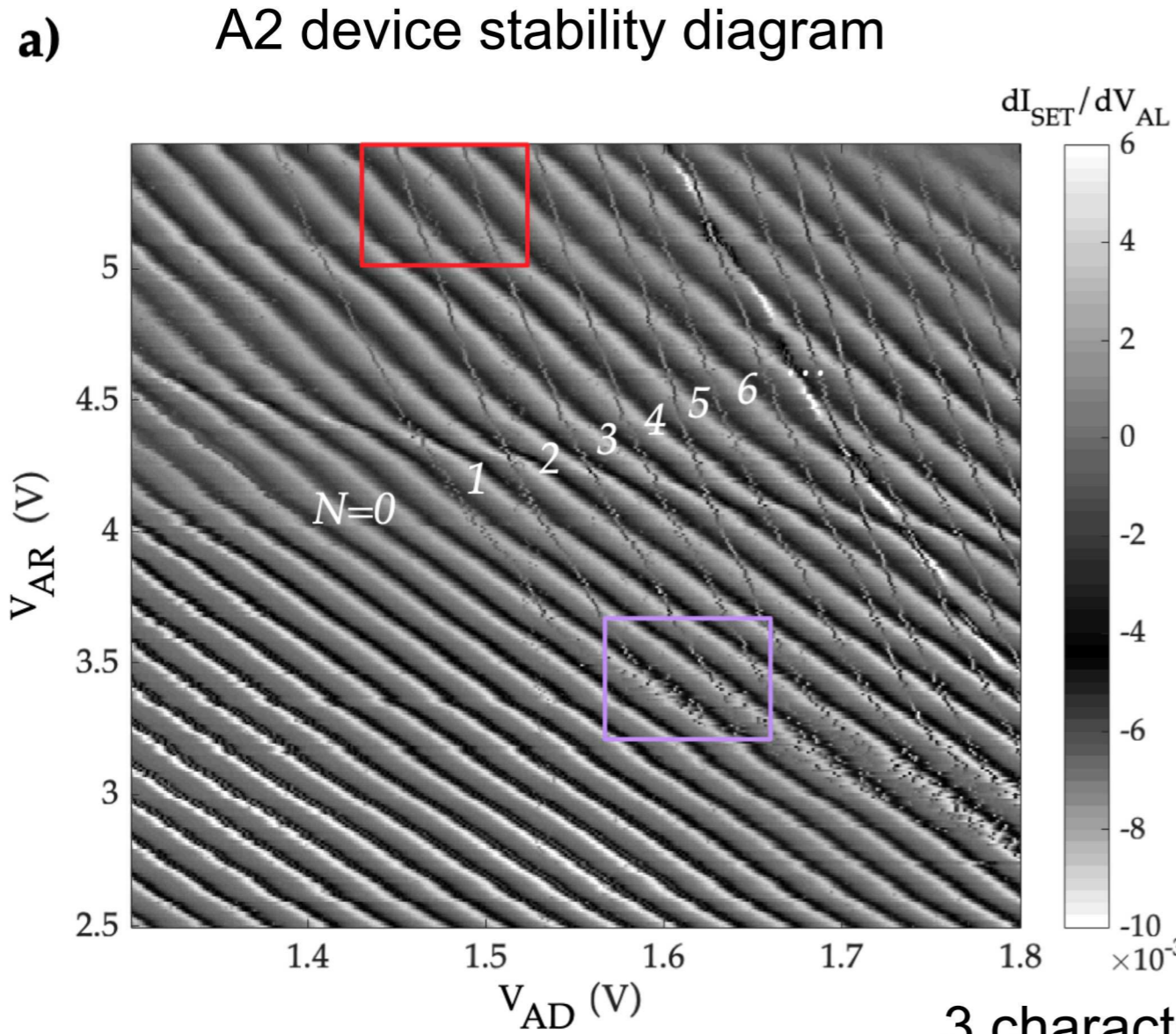
e) Conduction Band minima (meV)



f) Relative Conduction Band minima (meV)



Single electron regime

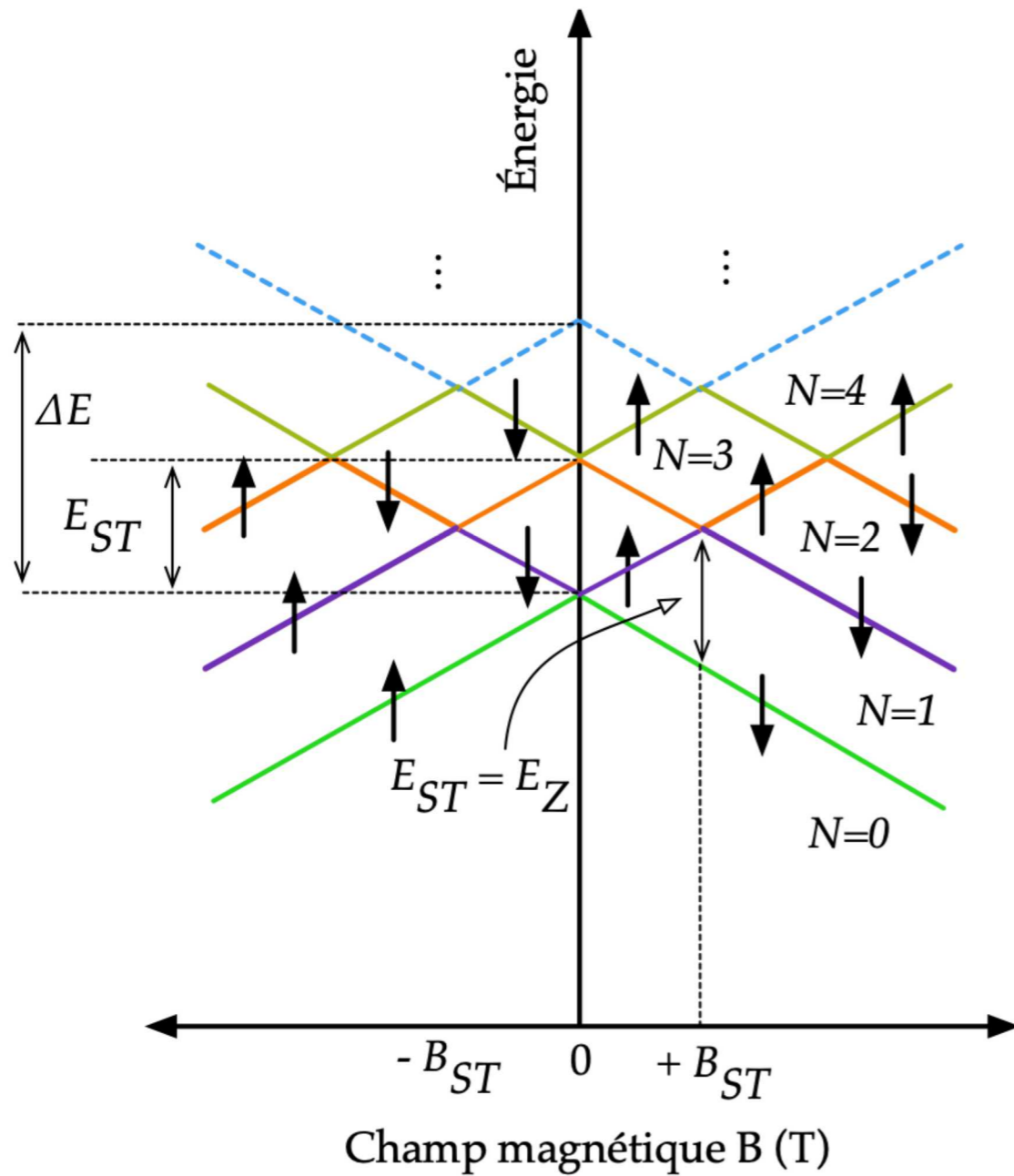


3 characteristics

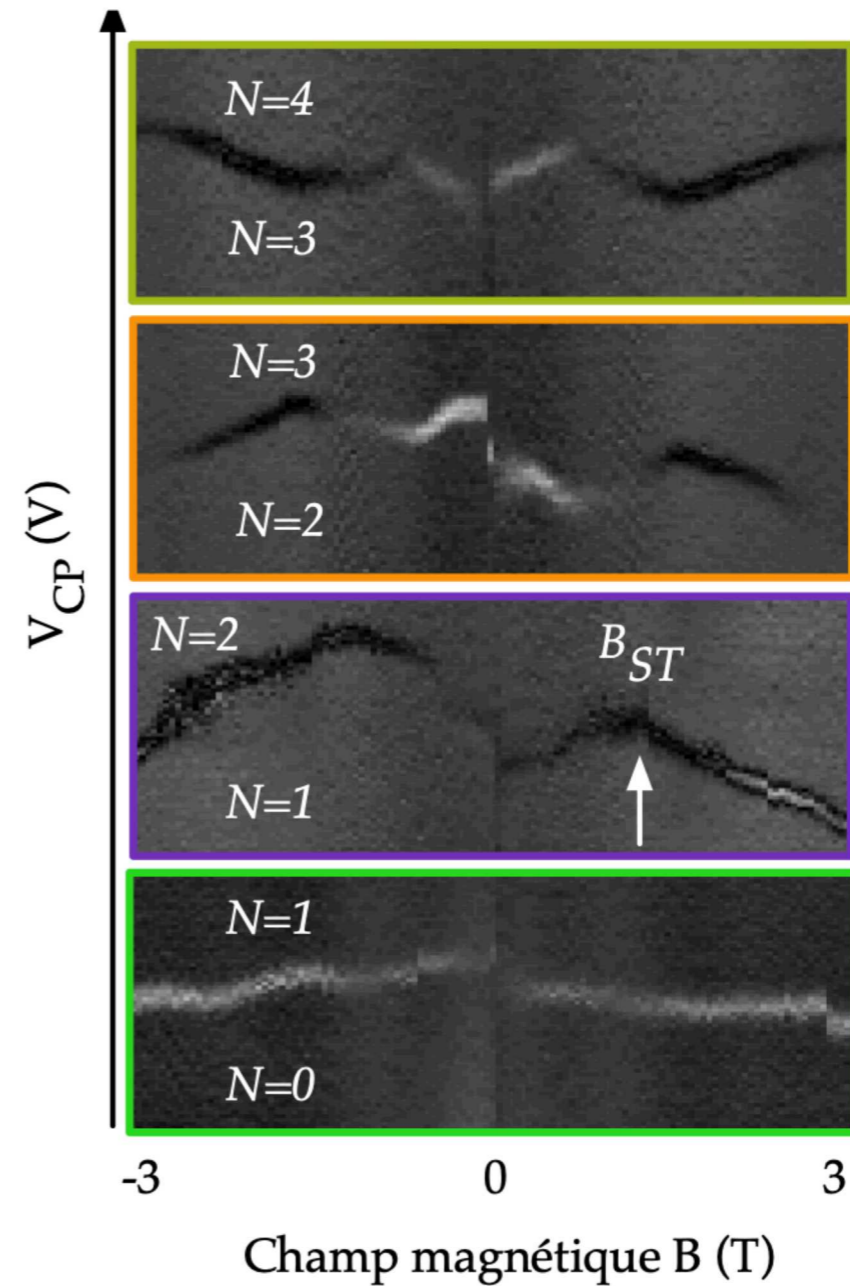
1. Vanishing of transitions
2. Pixelisation vs widening transitions
3. Charge transitions curvature

Single electron regime

a) QD spectrum schematics

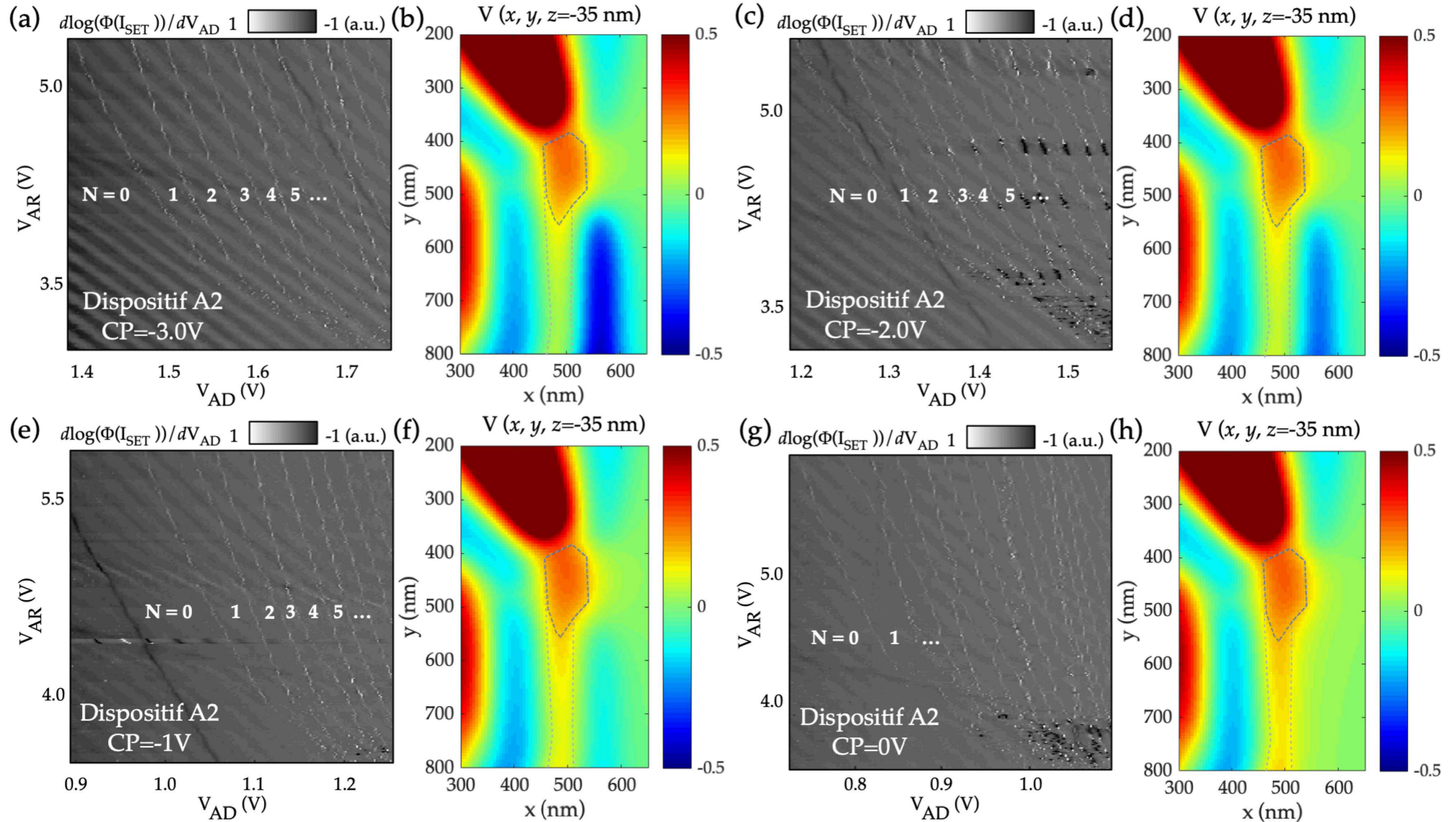


b) Magnétospectroscopie



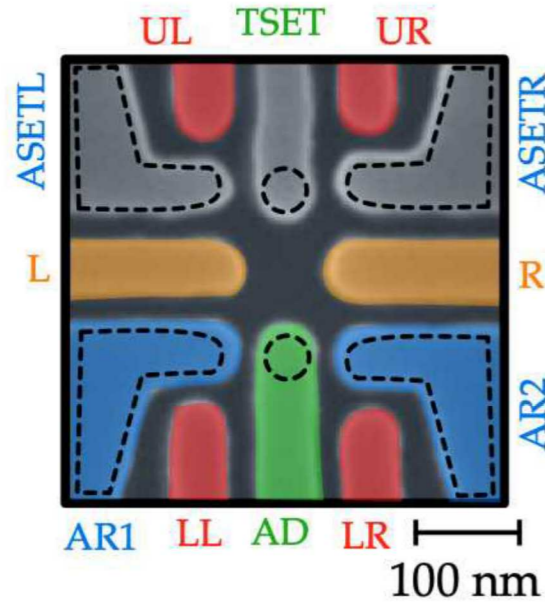
Behavior in magnetic field of the first transitions
consistent with 0 electrons

Electrostatic confinement

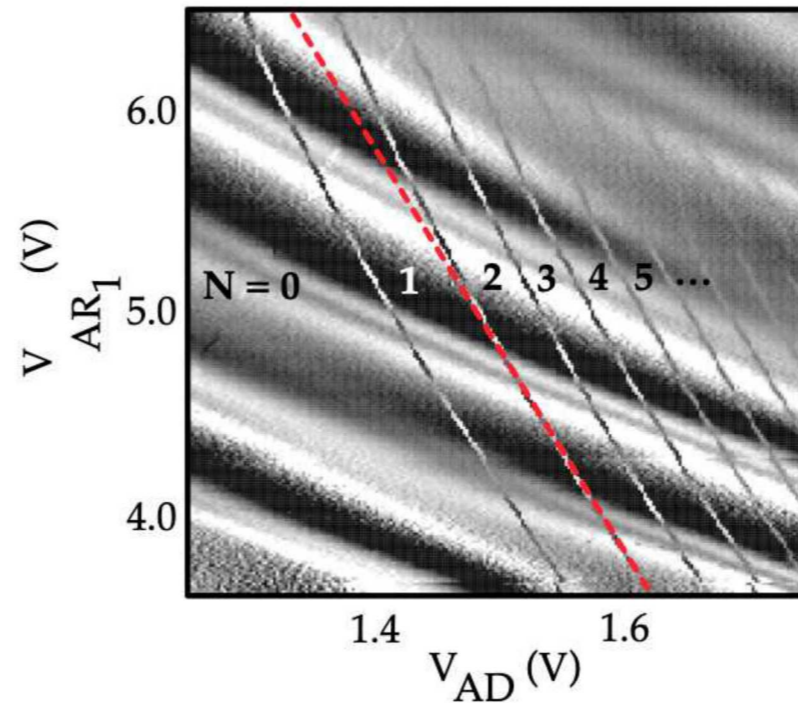


Single electron regime

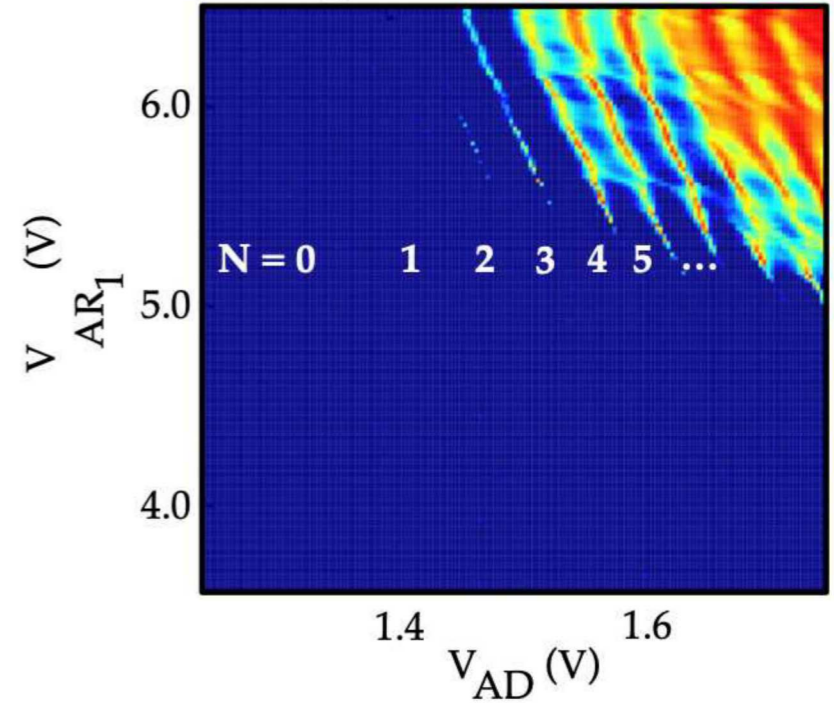
(a) **B device**



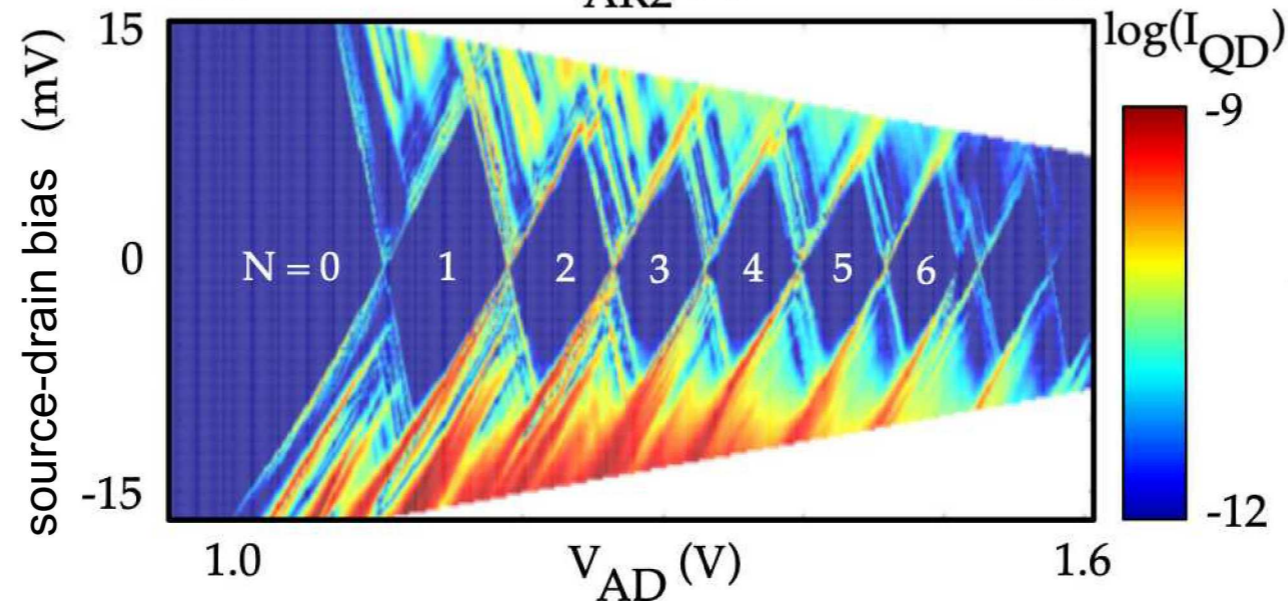
(b) $d\log(I_{\text{SET}})/dV_{\text{AD}} \times 10^{-3}$



(c) $\log(I_{\text{QD}})$



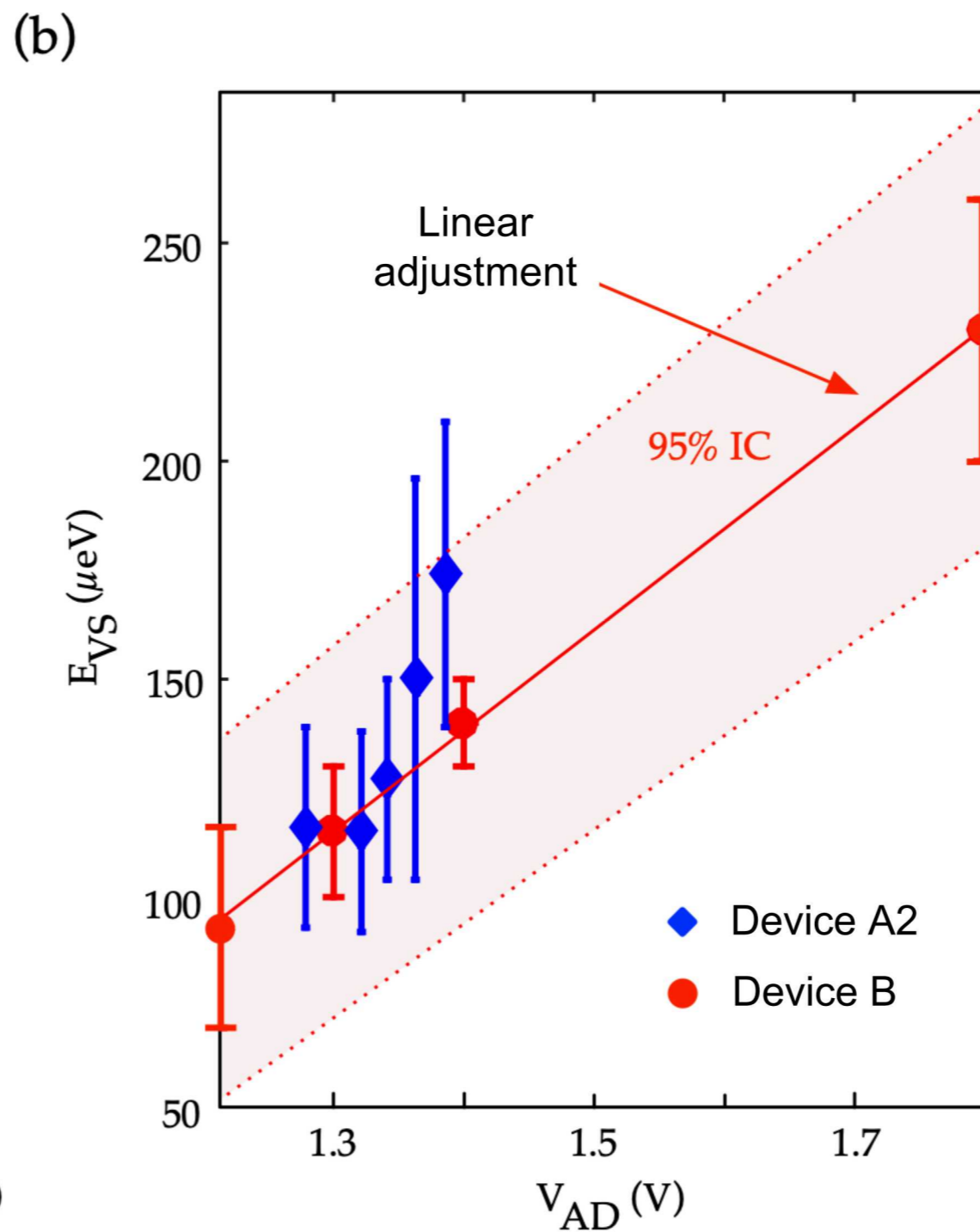
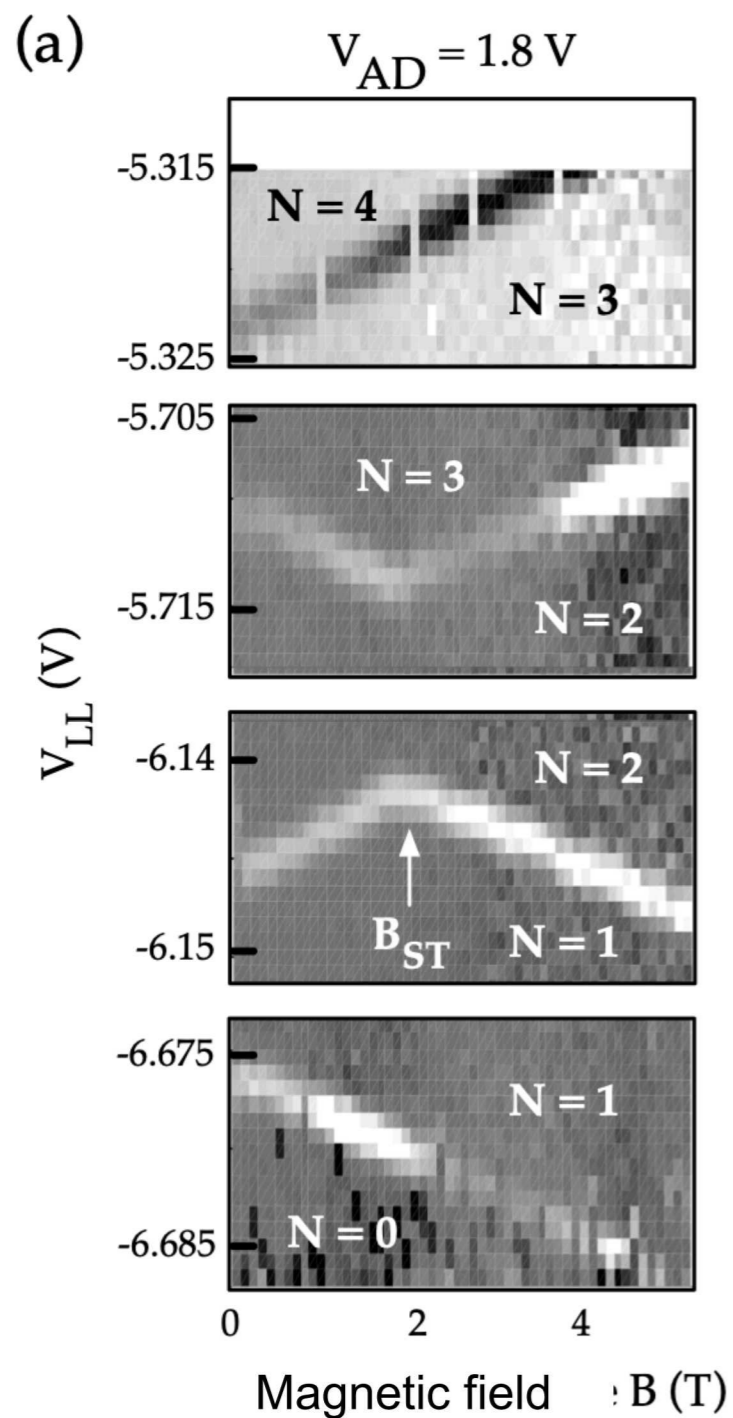
(d) V_{AR1} (V) 8.0 5.15
 V_{AR2} (V) 4.75 3.15



Estimated
 QD size:
 35-60 nm
 diameter

Reproducibility of typical
 characteristics in double-
 reservoir geometry

Valley splitting control



VS controlability

$8.1 \pm 0.6 \mu\text{eVm/MV}$,

Between 5 and 11

$\mu\text{eVm/MV}$ when

considering error

bars.

Multi-layers MOS

(Yang *et al.* 2013):

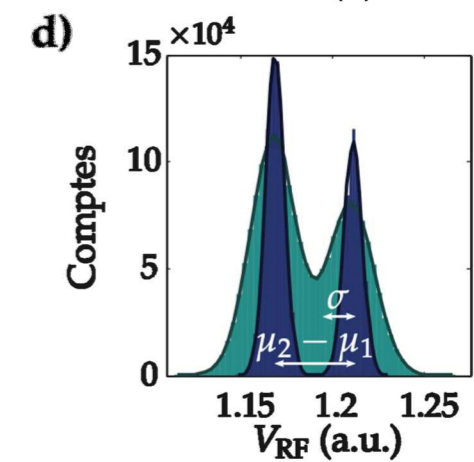
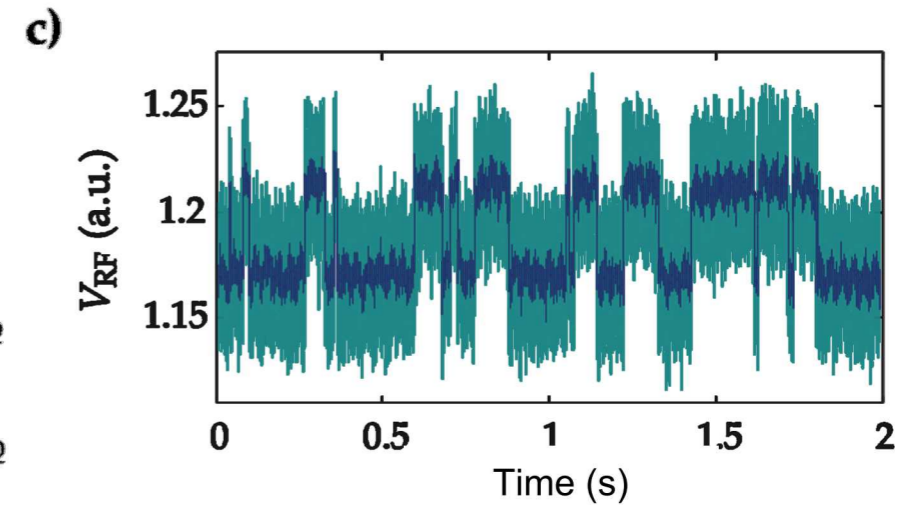
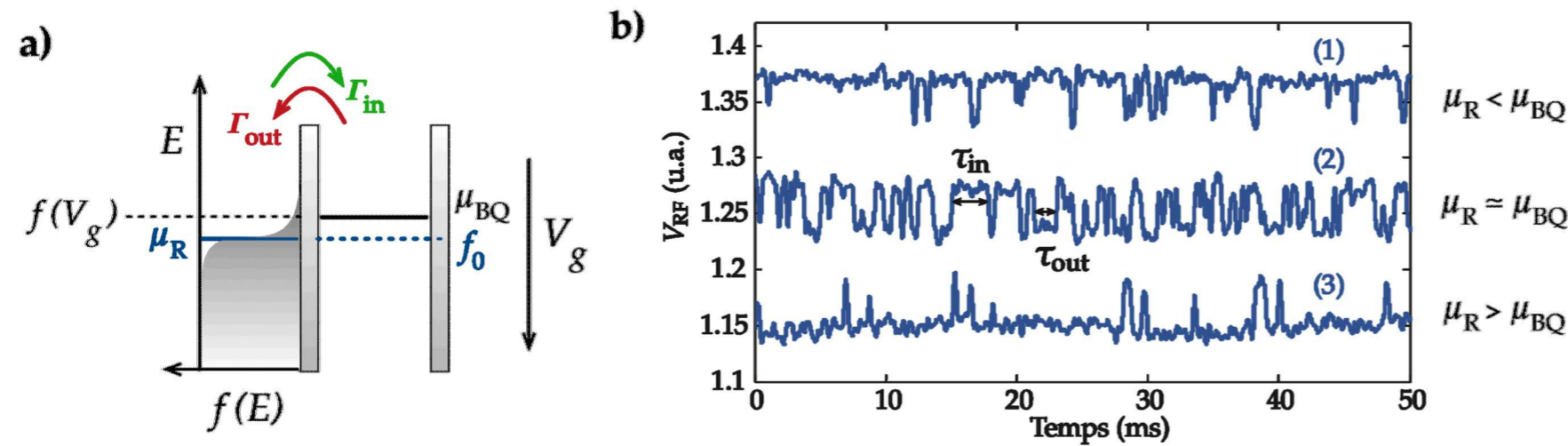
$5.12 \mu\text{eVm/MV}$

Tunnel rate control in the split accumulation gate structure

Tunnel rate measurement

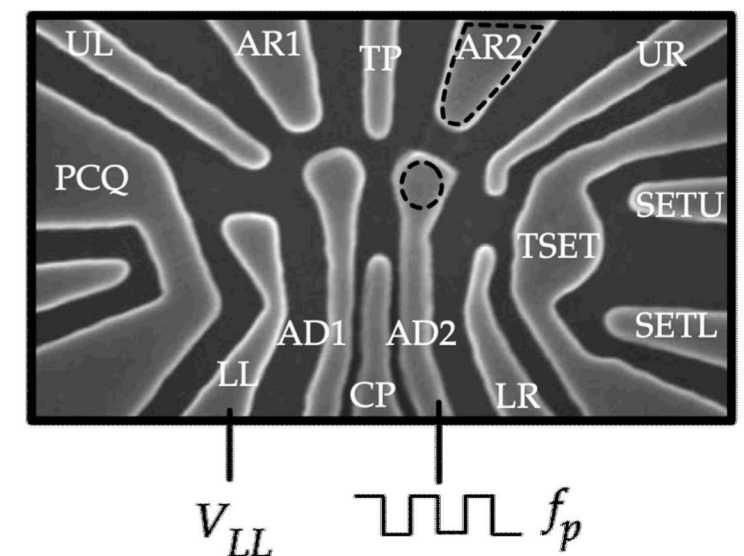
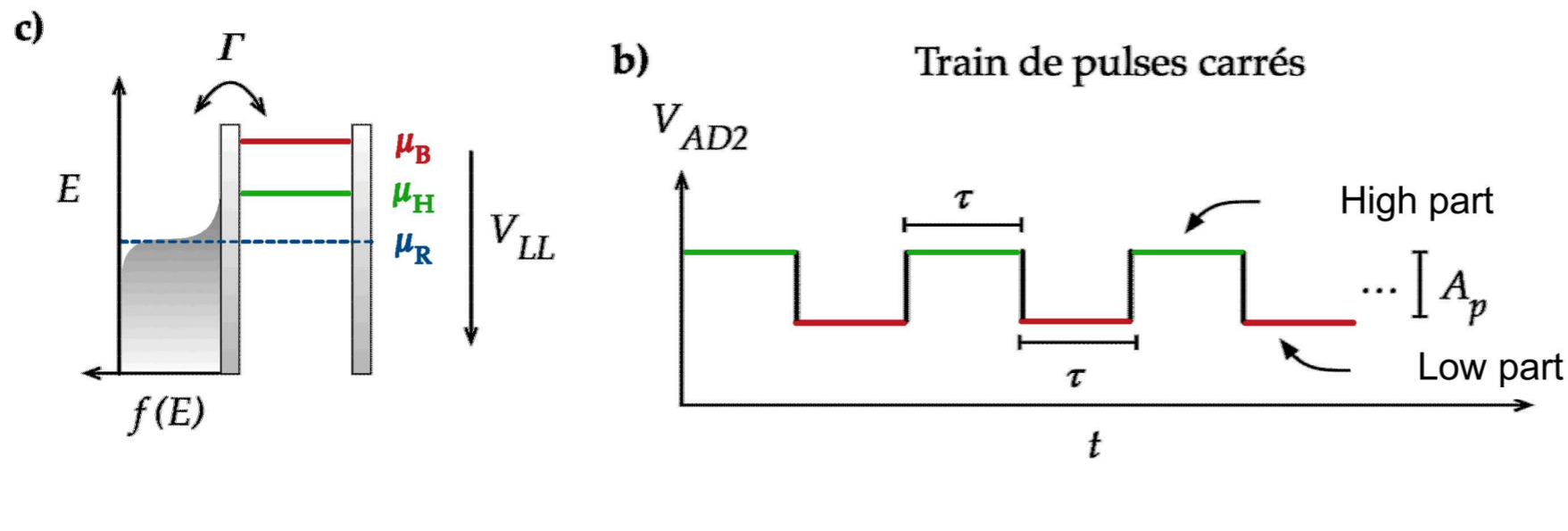
Method 1:

Real-time single shot statistics



Method 2:

Single-frequency pulse spectroscopy



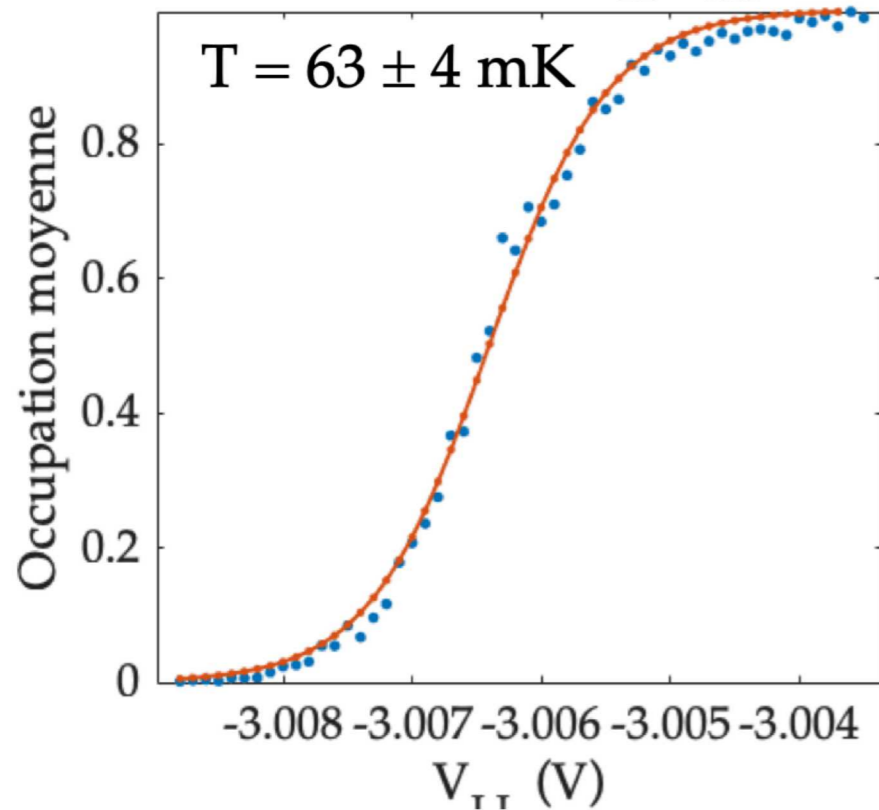
Tunnel rate measurements



Method 1:

Real-time single shot statistics

a) Mean occupation vs $V_{LL'}$, $V_{AR}=4.35$ V

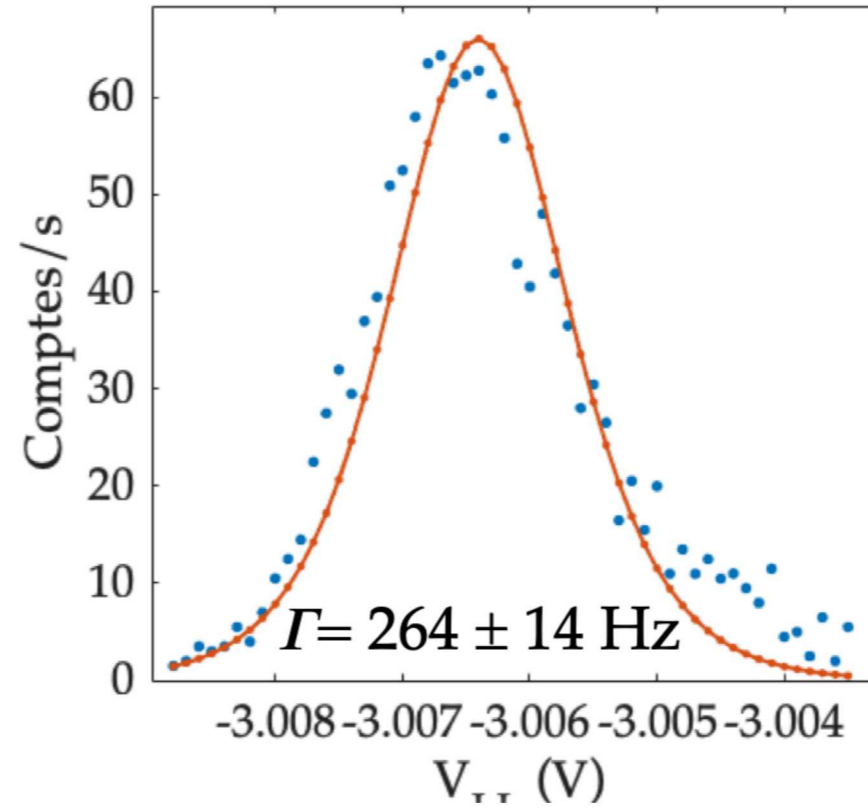


$$f(\mu_{BQ}) = \frac{\langle \tau_{out} \rangle}{\langle \tau_{in} \rangle + \langle \tau_{out} \rangle}$$

$$f(\mu_{BQ}) = \frac{1}{1 + e^{\frac{\mu_{BQ} - \mu_R}{k_B T}}}$$

Electronic temperatures:
30-73 mK

b) Counts/s vs $V_{LL'}$, $V_{AR}=4.35$ V

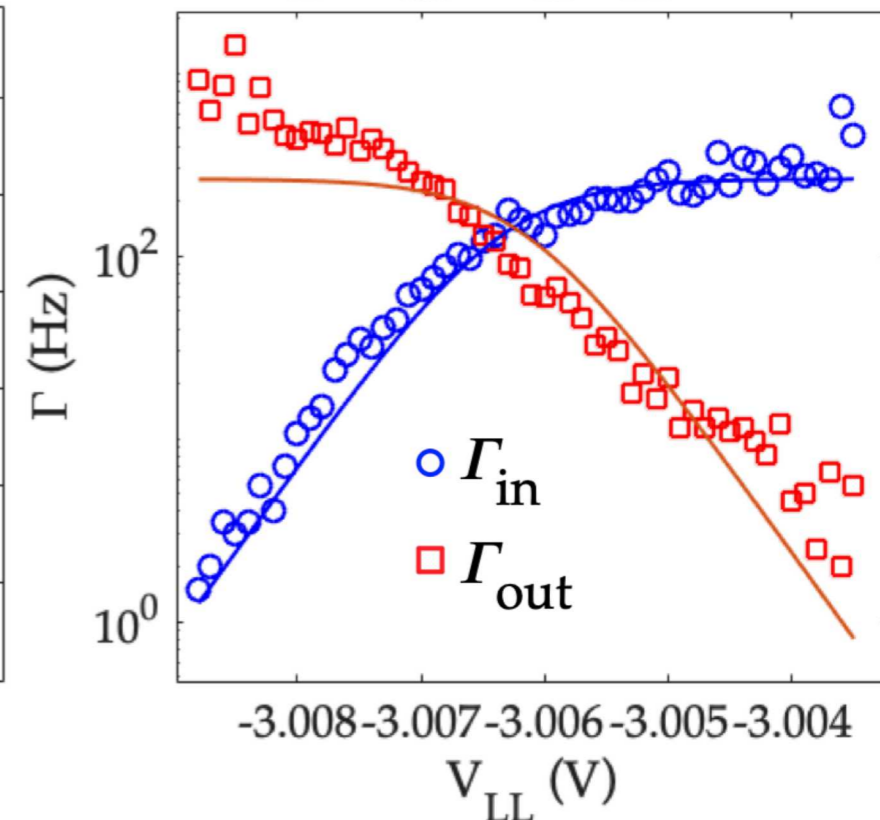


$$r_E = \frac{1}{\langle \tau_{in} \rangle + \langle \tau_{out} \rangle}$$

$$r_E = \Gamma f(1 - f)$$

Γ increases with V_{AR}

c) Γ_{in} et Γ_{out} vs $V_{LL'}$, $V_{AR}=4.35$ V



$$\Gamma_{in} = \Gamma f(\mu_{BQ}),$$

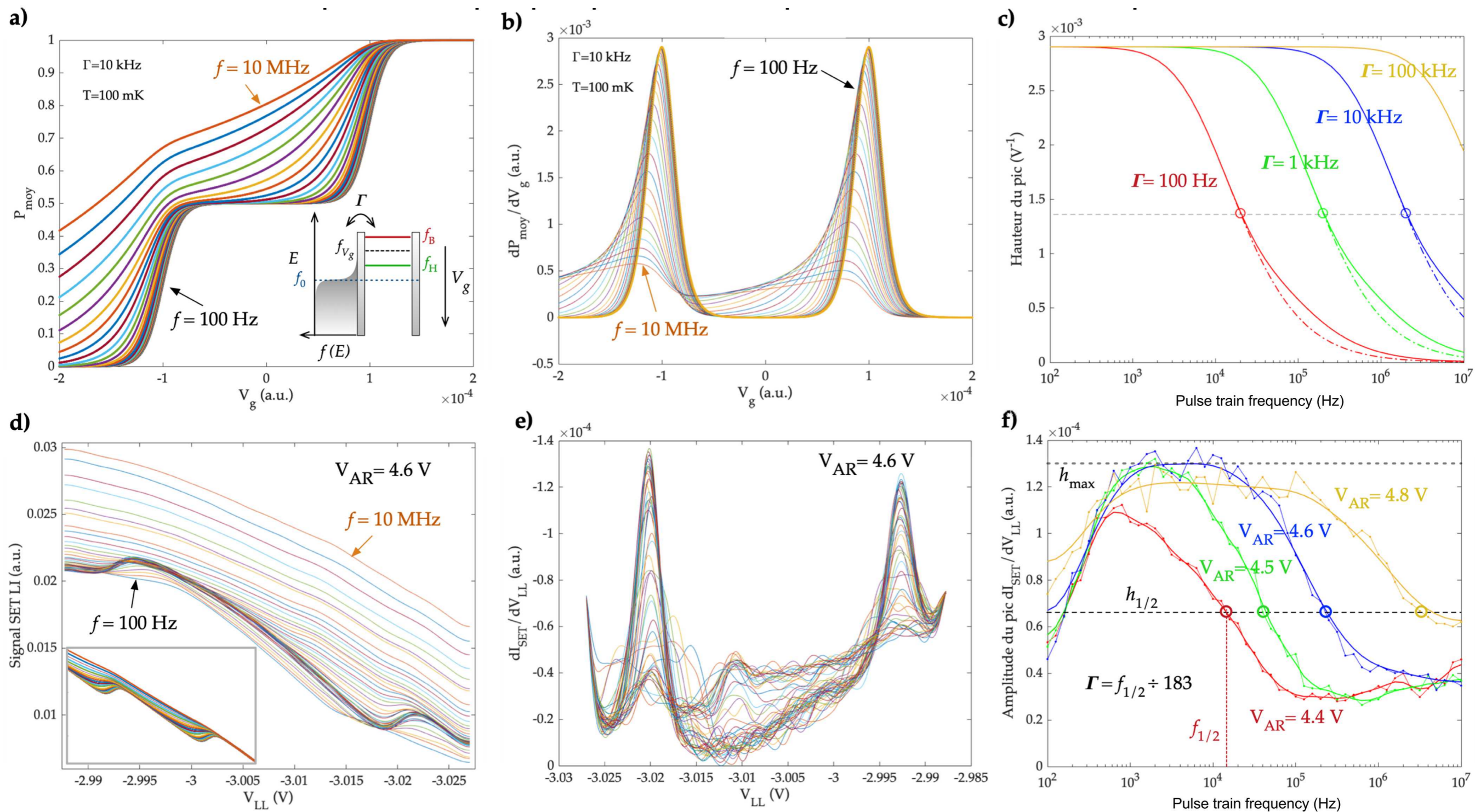
$$\Gamma_{out} = \Gamma(1 - f(\mu_{BQ})),$$

Excited states
contribution neglected

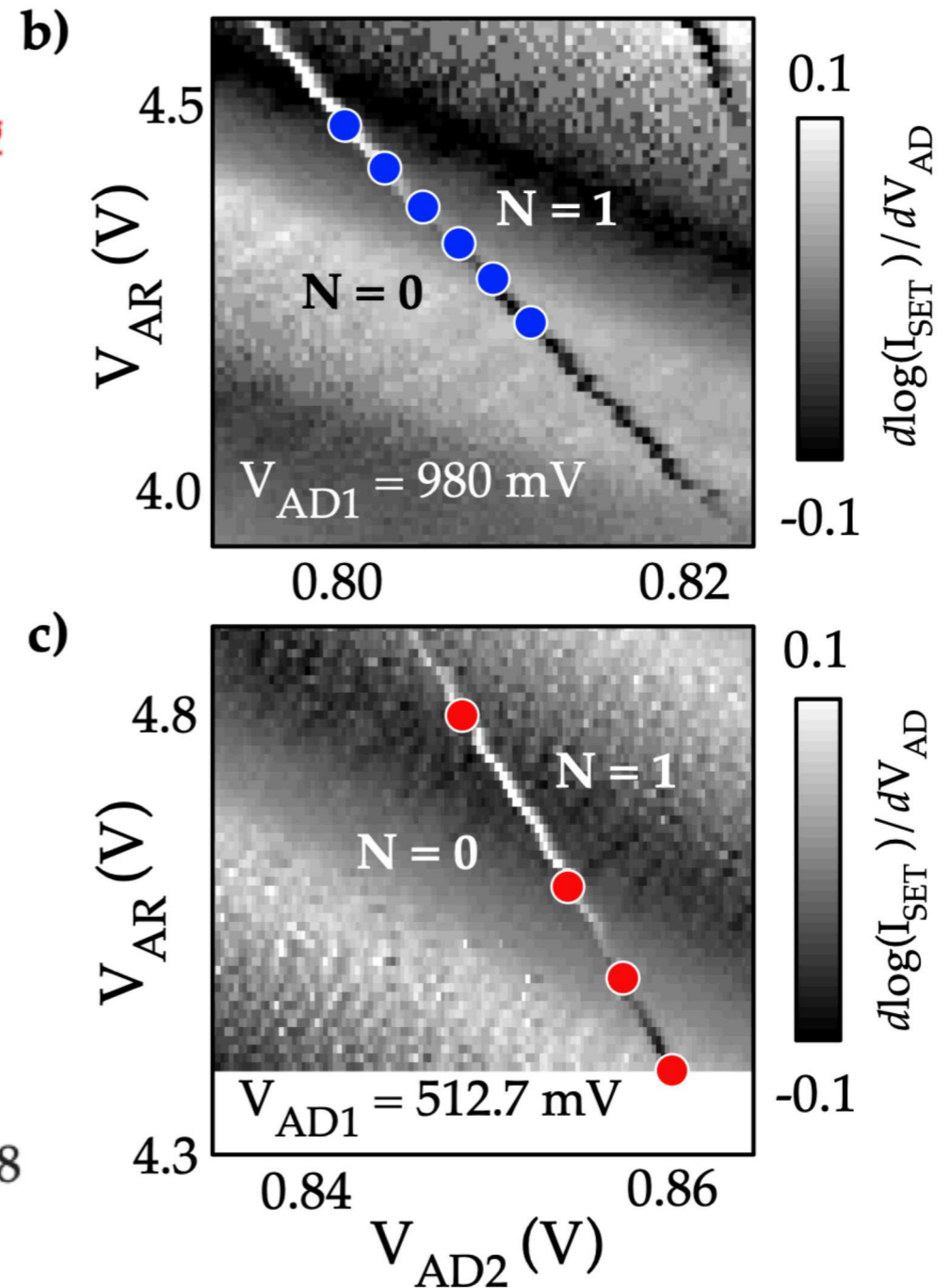
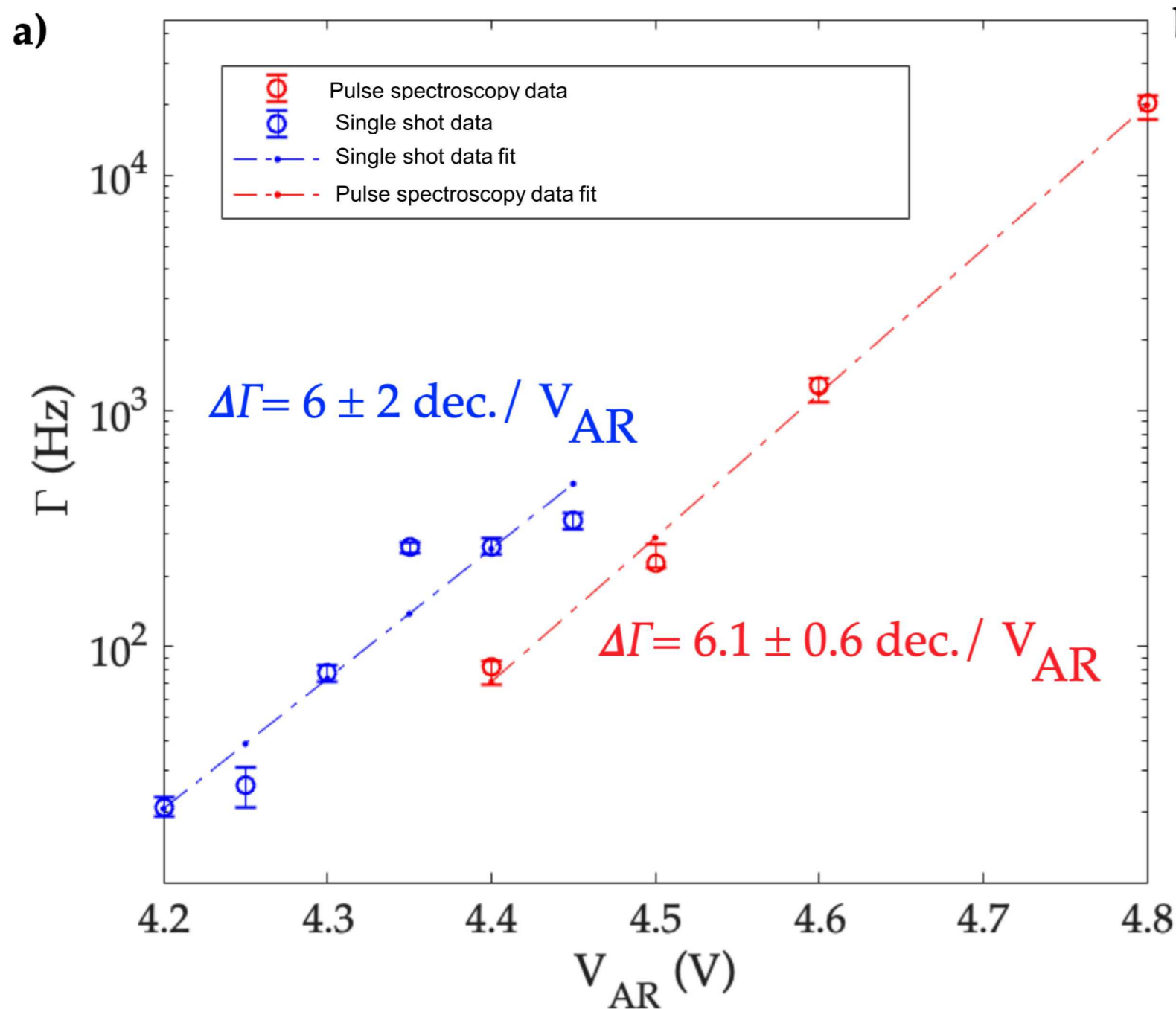
Tunnel rate measurement

Method 2:

Single-frequency pulse spectroscopy



Tunnel rate control using the reservoir accumulation gate



Tunnel rate control with the reservoir accumulation gate

$$\beta_{g1,g2} \equiv \beta_{g1} - \beta_{g2} = \frac{\Delta\Gamma_{g1,g2}}{\Delta\mu_{g1}}$$

Tunnel rate variation

in decades

Chemical potential

variation in meV

Measure of the *control*

orthogonality:

Level of control

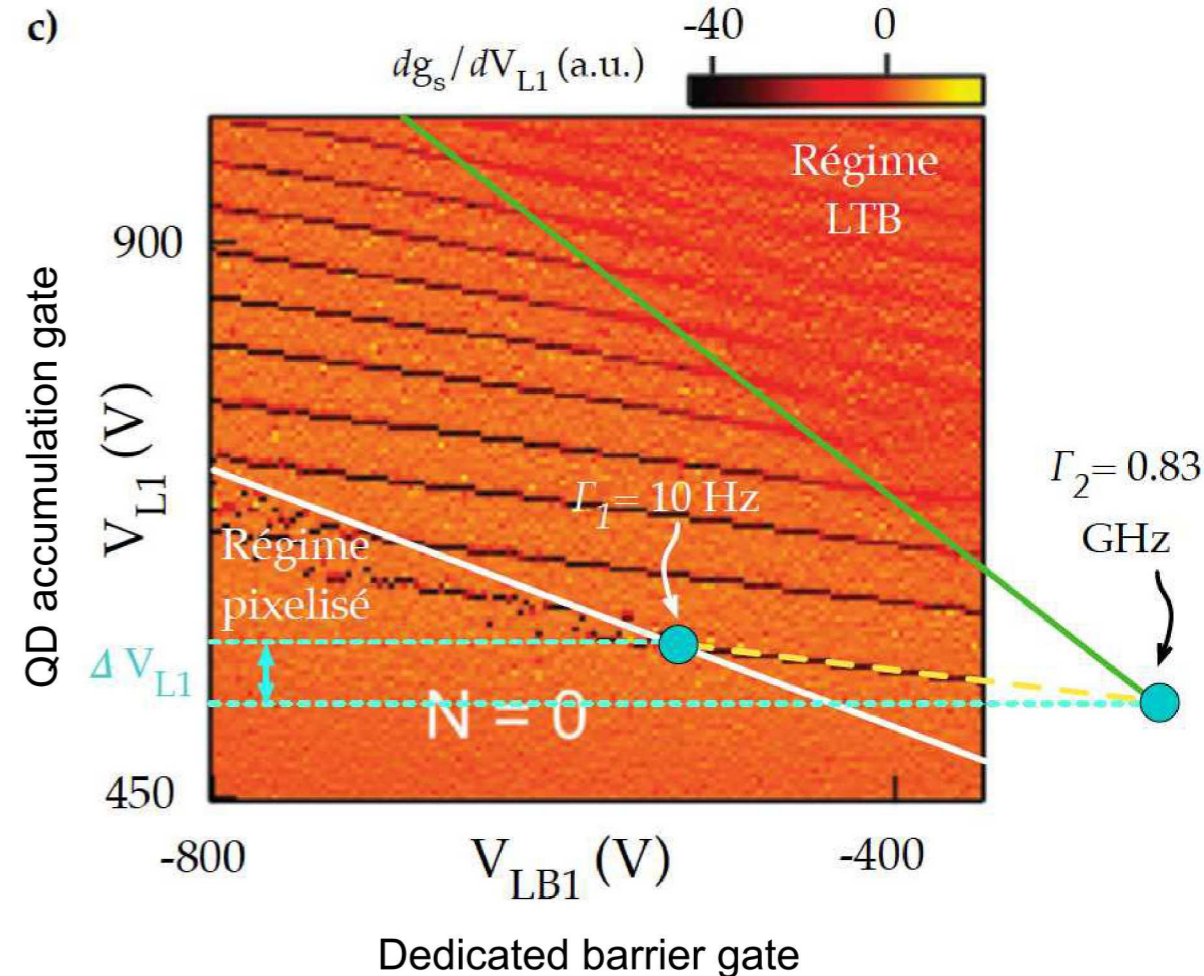
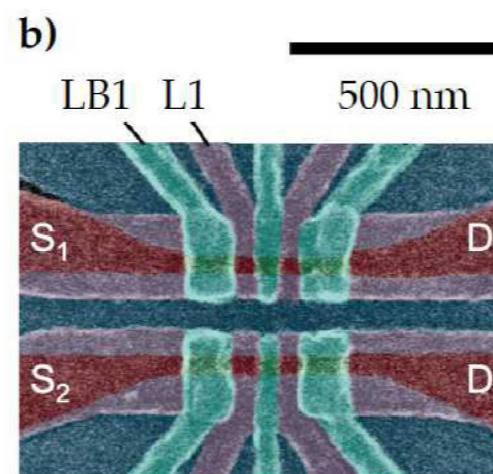
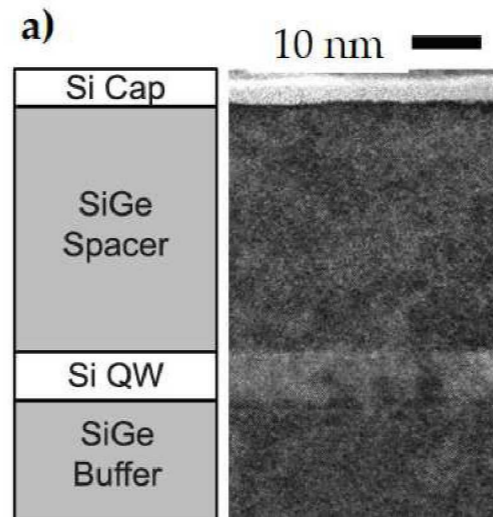
independance between

tunnel rate and QD

occupation

Allows comparison

between different devices



3 performance criterias



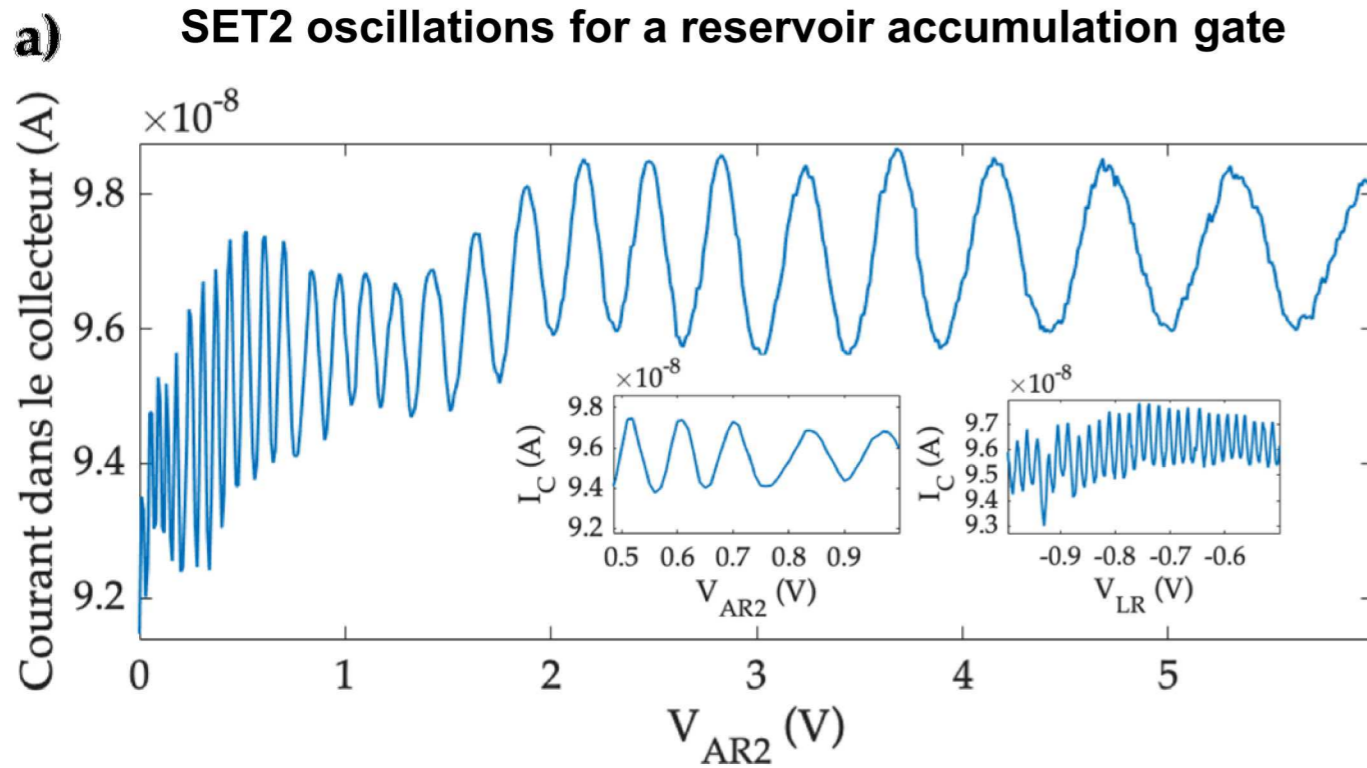
Device:	A1	A2	B	Litterature
QD diamenter	-	48-77 nm	35-60 nm	20-58 nm [1,2,3,4,5]
Valley splitting	-	-	$\beta = [5, 11]$ $\mu\text{eVm/MV}$	$\beta = 5.12$ $\mu\text{eVm/MV}$ [6]
Tunnel rate	$\beta = 0.9 \pm 0.3$ dec/meV	-	-	$\beta = [1.0, 2.4]$ dec/meV [1]

[1]: D. M. Zajac et al., APL 106, 223507 (2015)
 [2]: S. J. Angus et al., Nano Letters 7, 2051-5 (2007)
 [3]: M. Veldhorst et al., Nat. Nano., 1-5 (2014)

[4]: C. H. Yang et al., Nat. Electronics 2, 151 (2019)
 [5]: M. Veldhorst et al., Nature, 1-5 (2015)
 [6]: C. H. Yang et al., Nat. Comm., 3069, 2013

Role of the reservoir charge density in split accumulation gate structure operation

A model for the charge transition curvature



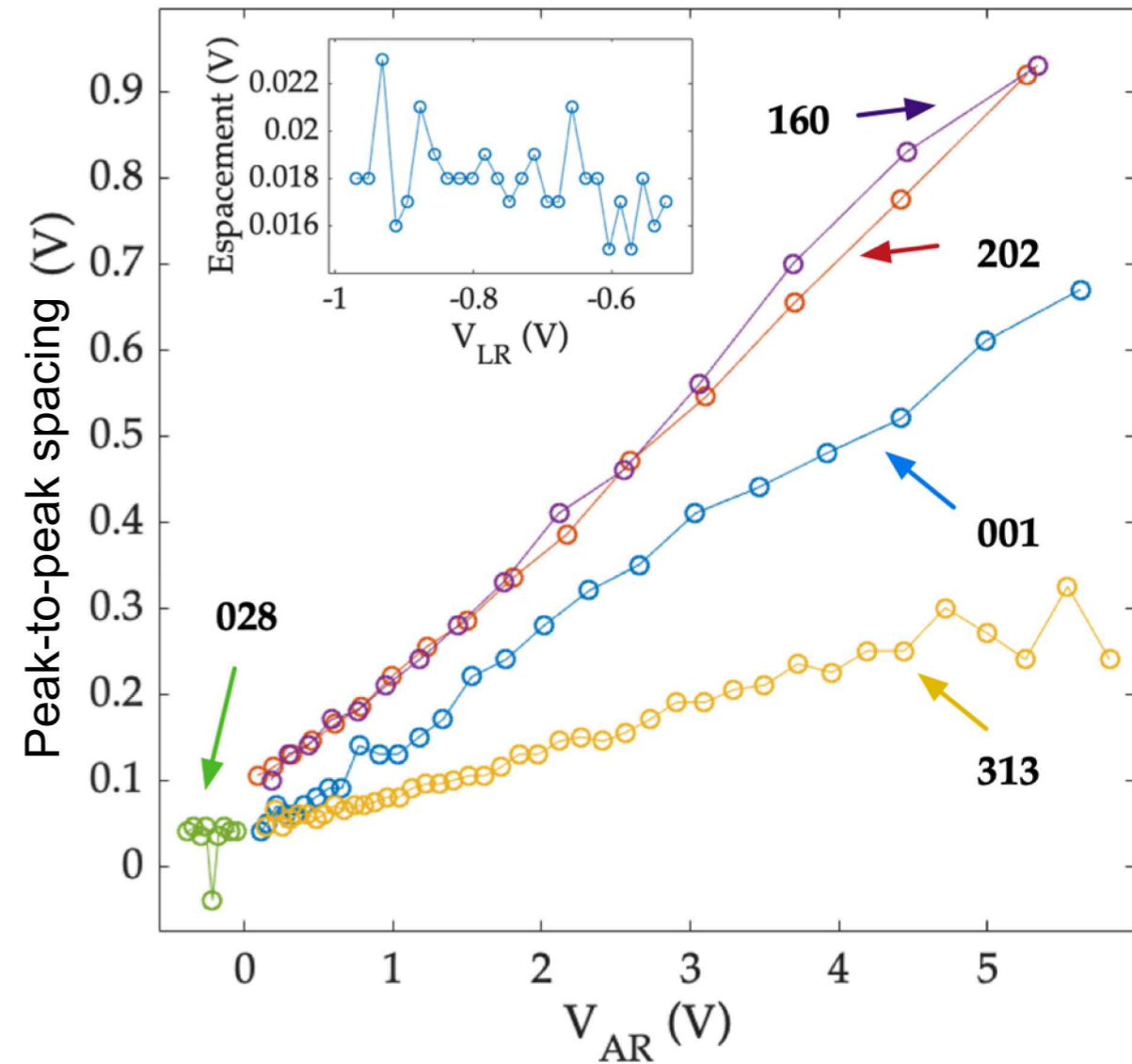
Linear increase of
oscillation period:

$$P_{AR \rightarrow SET} = \Theta V_{AR} + P_{AR \rightarrow SET_0}$$

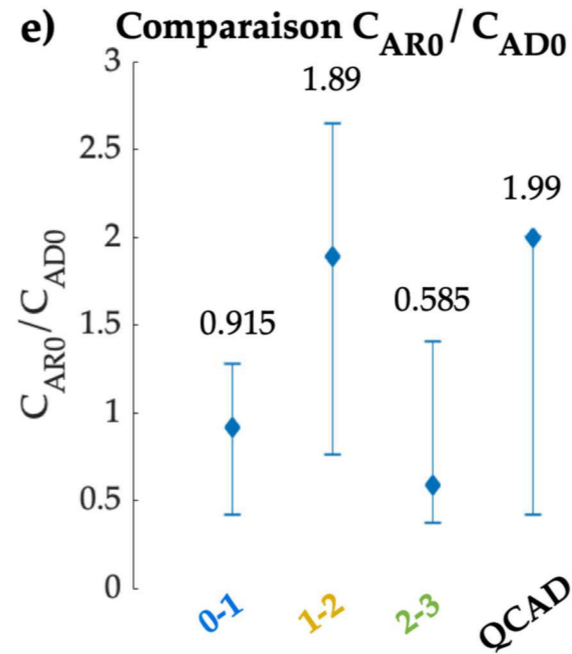
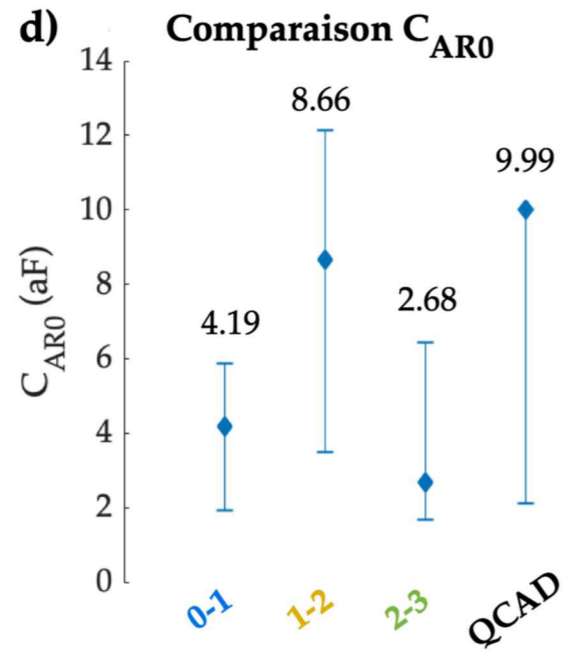
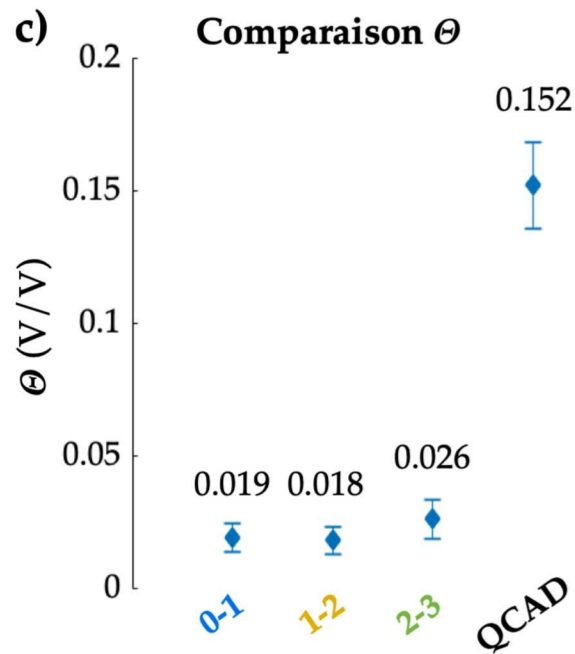
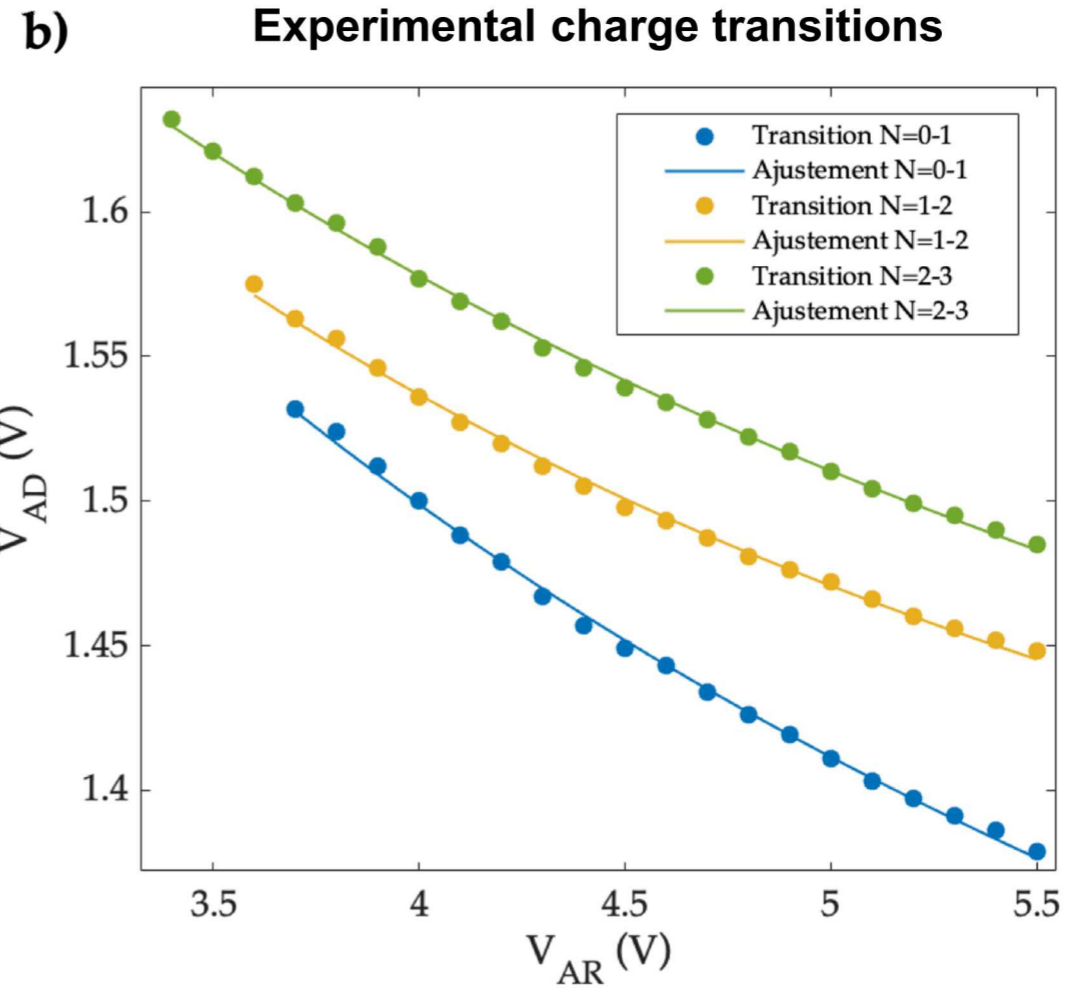
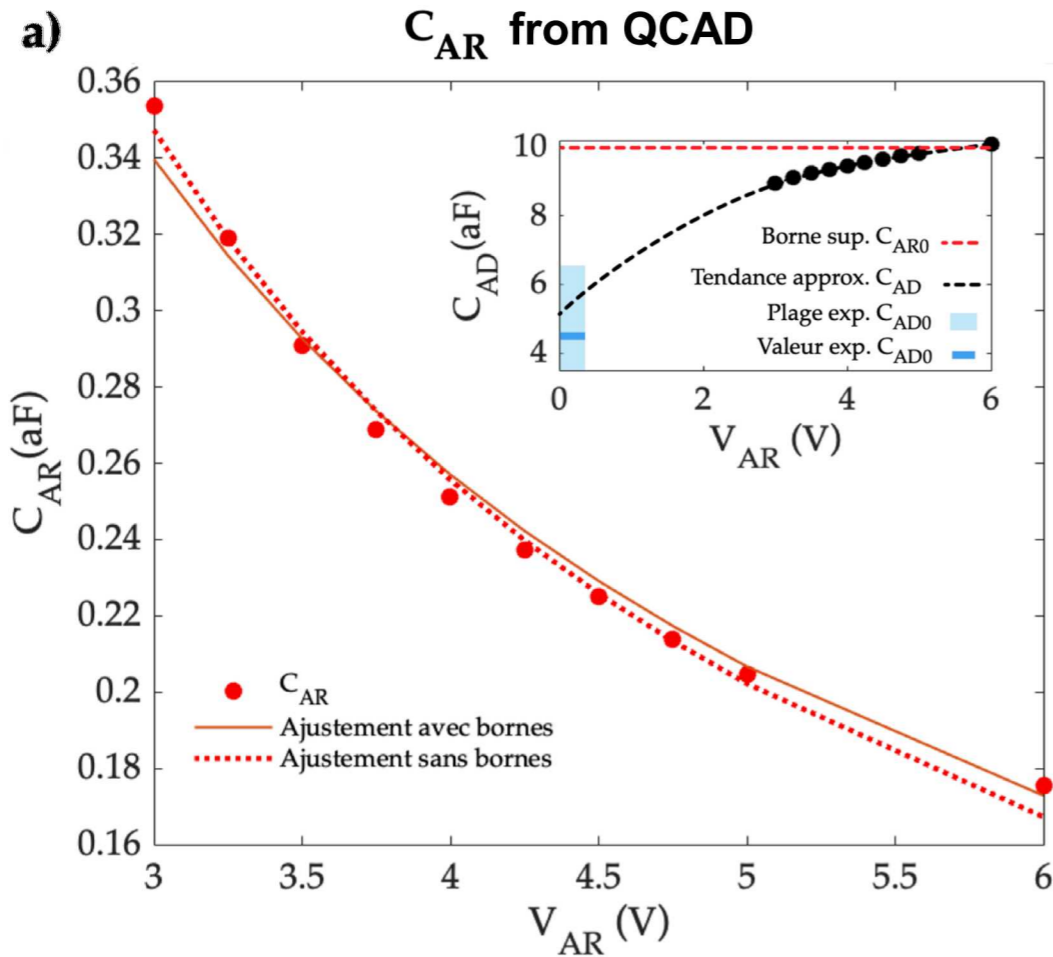
Gate-island capacitance vs voltage:

$$C_{AR \rightarrow SET} = \frac{1}{\frac{\Theta V_{AR}}{e} + \frac{1}{C_{AR \rightarrow SET_0}}}$$

b) Peak-to-peak spacing vs V_{AR}



Application to data



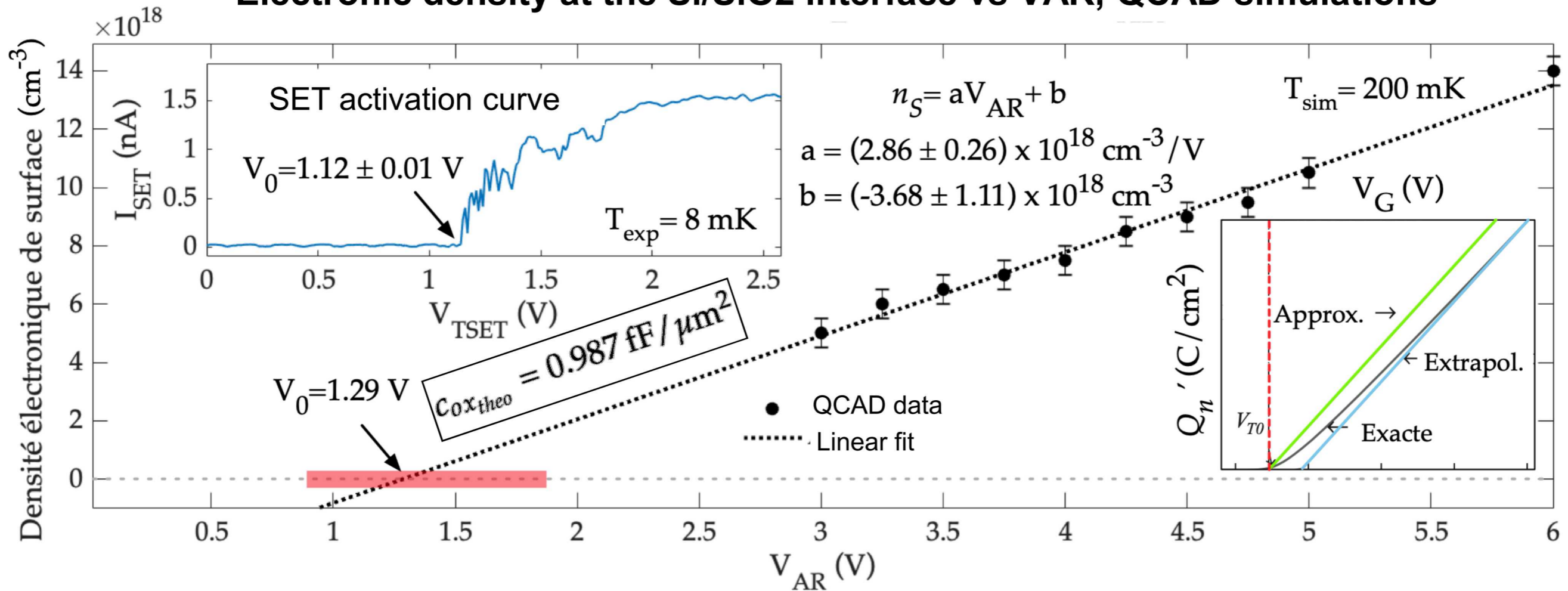
Charge transition condition:

$$V_{AD} = -\frac{1}{C_{AD0}} \left[\frac{V_{AR} + \frac{(\mu_N - \eta_N)}{e}}{\frac{\theta}{e} V_{AR} + \frac{1}{C_{AR0}}} \right] + \Omega_N$$

Role of the reservoir charge density



Electronic density at the Si/SiO2 interface vs VAR, QCAD simulations



Effective gate voltage caused by adding charges in the reservoir:

$$\delta V_{AR(+N_R)} = \frac{-eN_R}{C_{Rtot}} \frac{C_{R \rightarrow SET}}{C_{AR \rightarrow SET_0}}$$

$$V_{AReff} = V_{AR} + \delta V_{AR(+N_R)}$$

$$N_R = \Delta n_S S_R d_{inv}$$

Falling back on the empirical model:

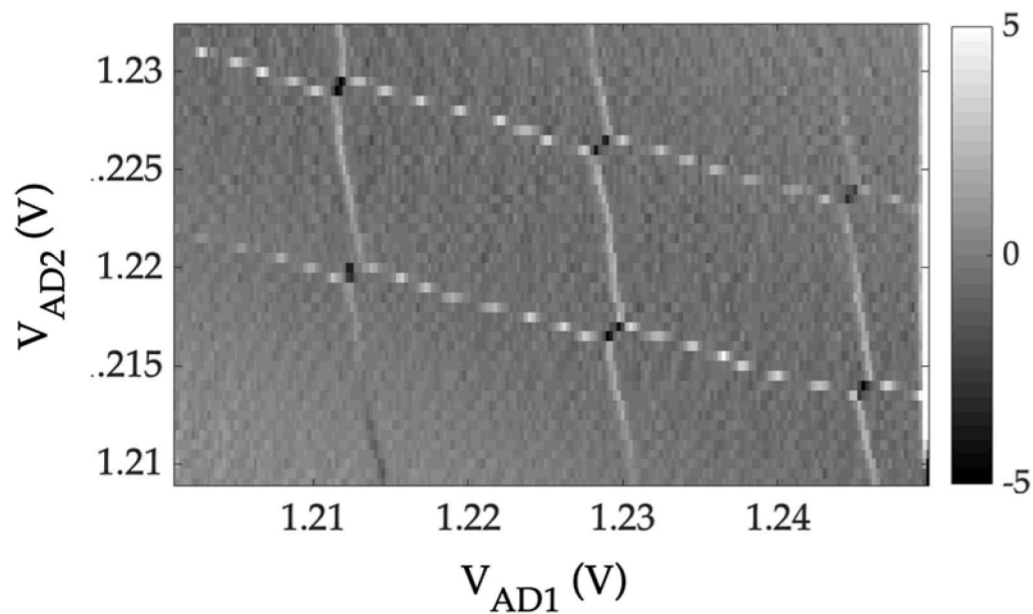
$$C_{AR \rightarrow SET} = \frac{1}{\frac{1}{C_{AR \rightarrow SET_0}} + \frac{1}{e} \frac{C_{AR \rightarrow R} C_{R \rightarrow SET}}{C_{Rtot} C_{AR \rightarrow SET_0}} V_{AR}}$$

$$= \frac{1}{\frac{1}{C_{AR \rightarrow SET_0}} + \frac{\Theta}{e} V_{AR}}$$

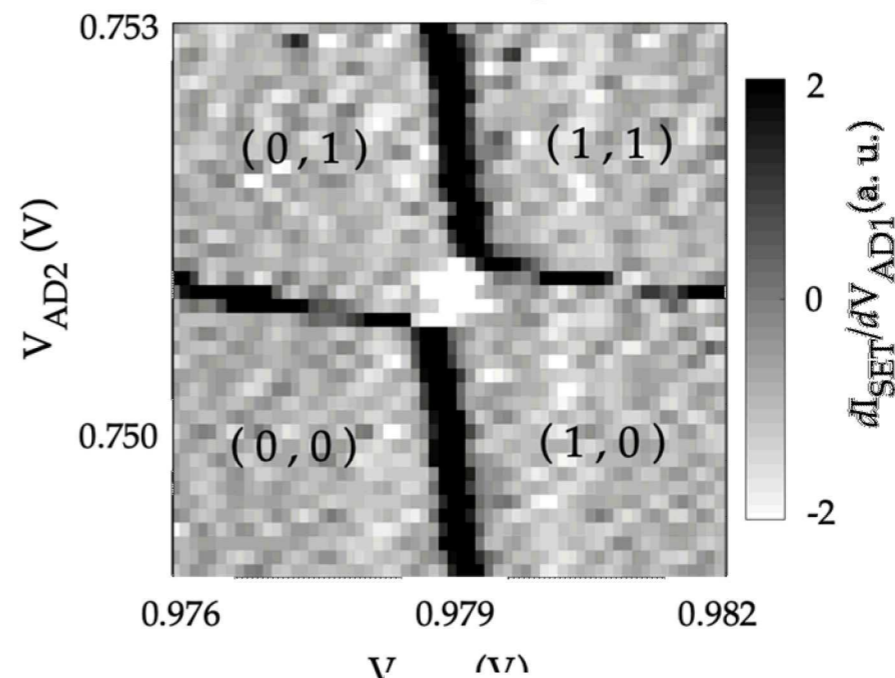
Scale-up of the split accumulation gate structure

Scaling-up: double quantum dot

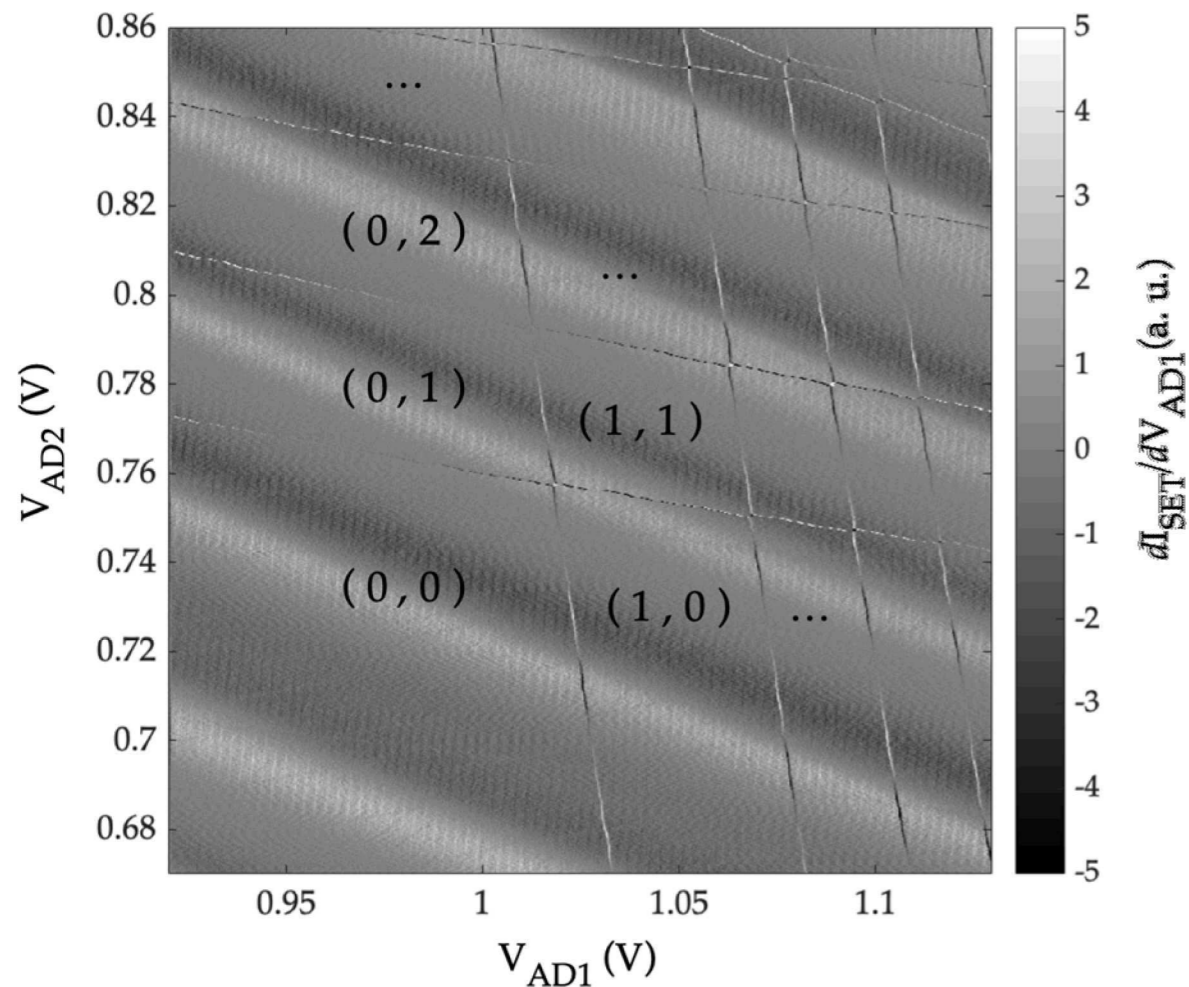
a) DQD, many-electrons regime



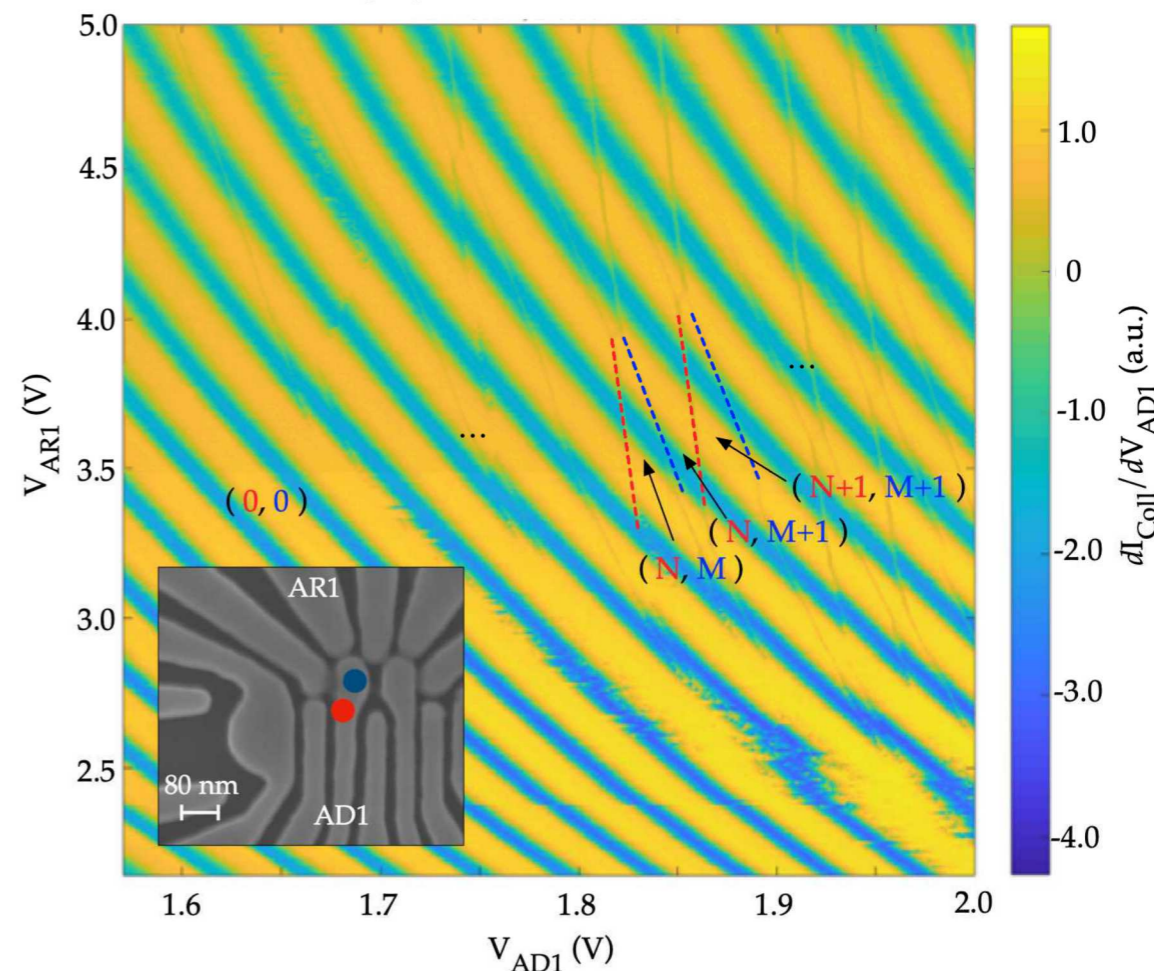
Inter-QD transition in the few-electrons regime



b) DQD, few-electrons regime

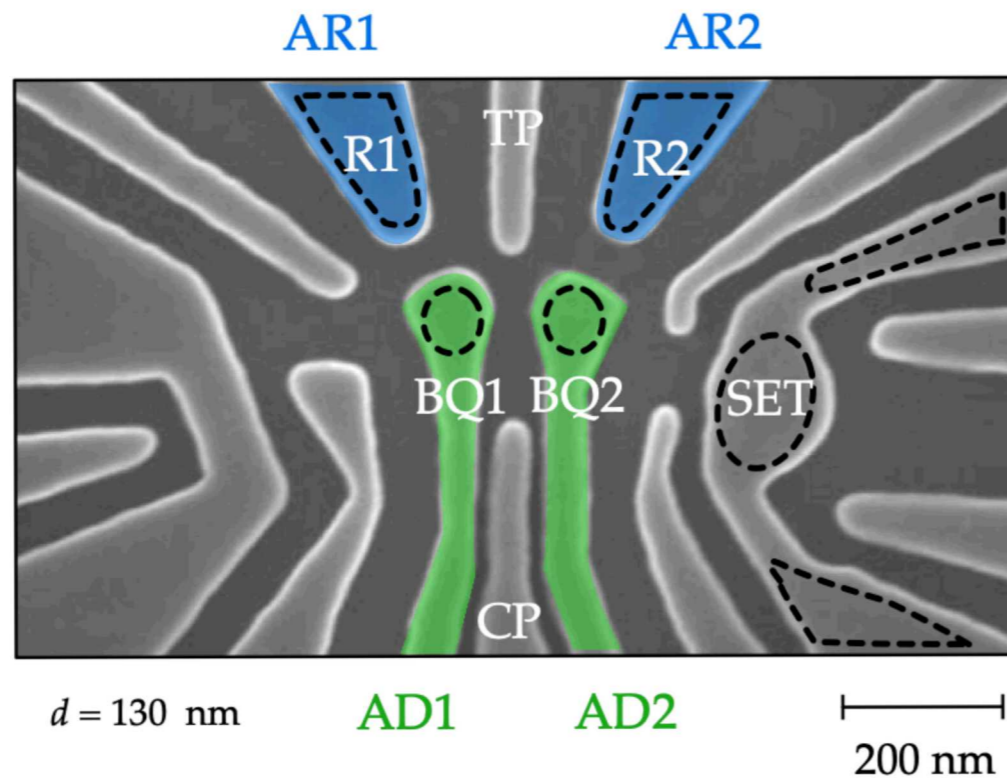


Non-lithographic DQD under AD1, A2 device

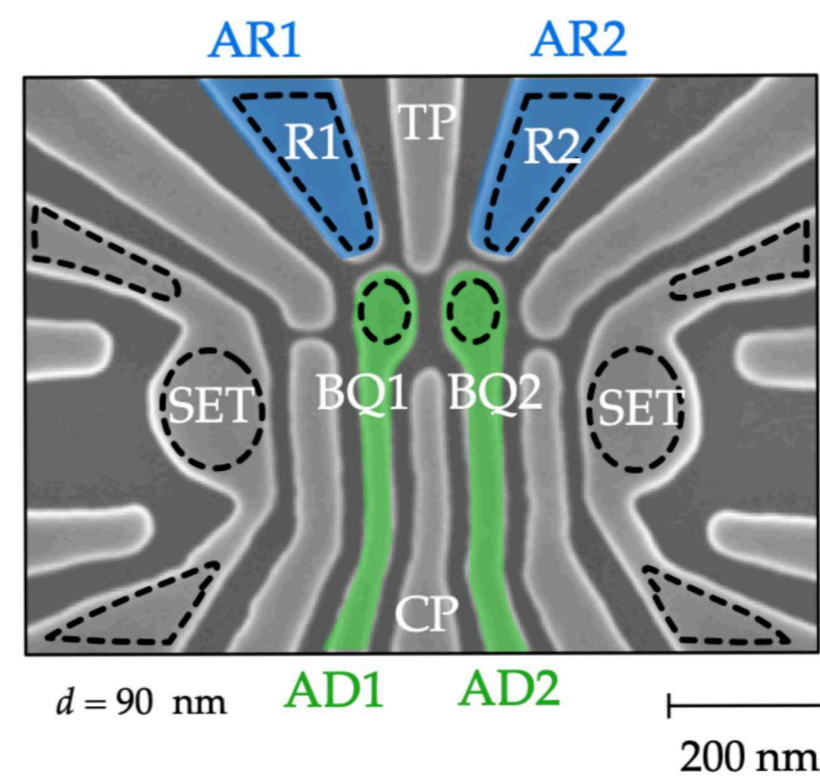


Dimensions vs inter-QD coupling: comparison

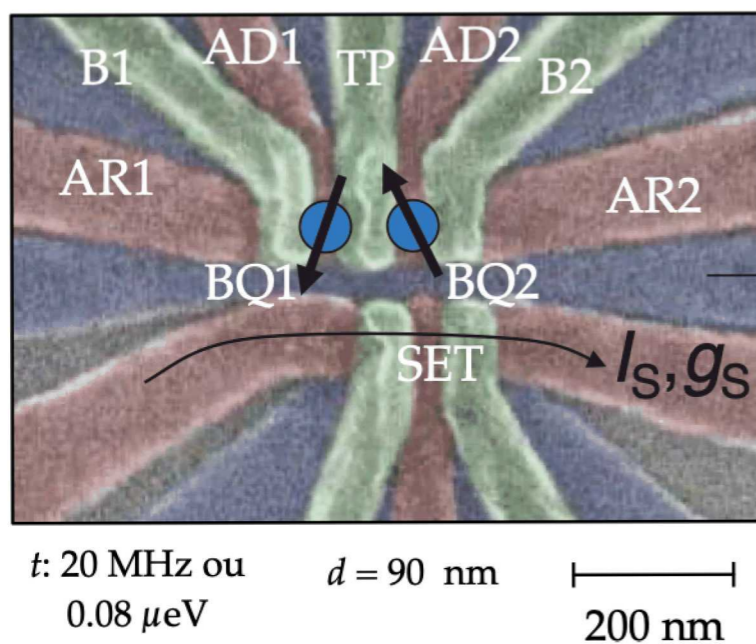
a) A1 device



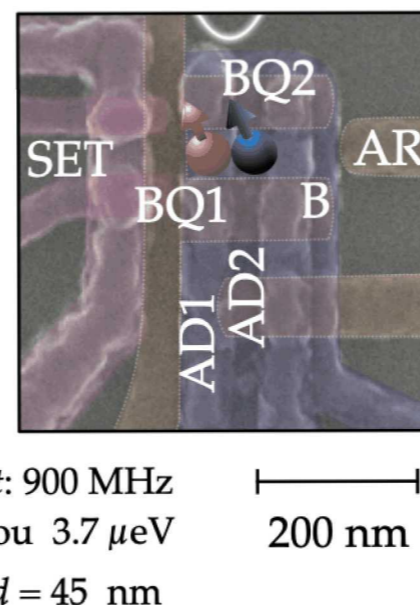
b) A2 device



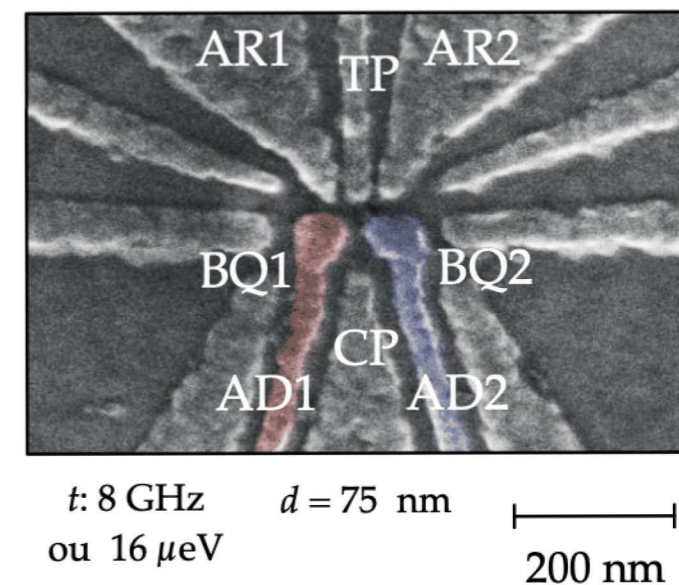
c) D. Zajac *et al.* 2018



d) M. Veldhorst *et al.* 2015



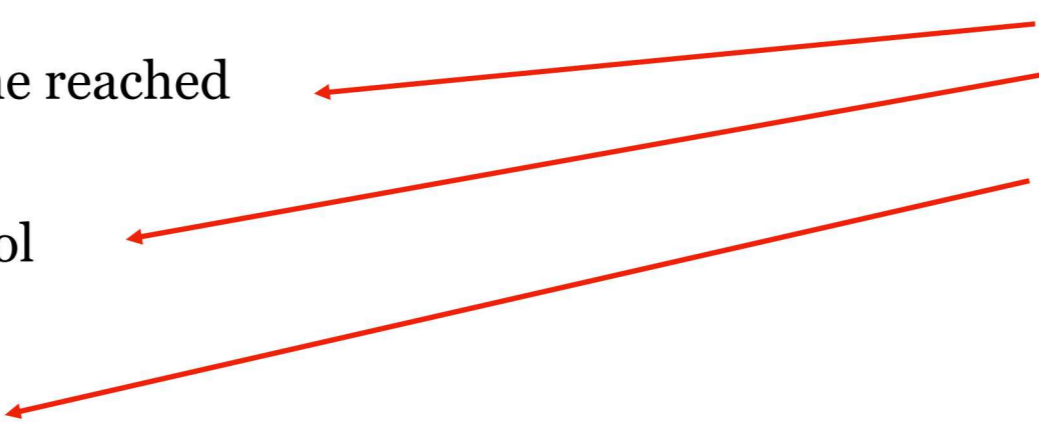
e) N. Samkharadze *et al.* 2018





Conclusion

Main results of the thesis

1. Single-electron regime reached
 2. Valley splitting control
 3. Tunnel rate control
 1. Demonstration of an alternative control method with the reservoir accumulation gate
 2. Definition of a performance criterion allowing comparison between different geometries-> Control orthogonality
 3. Development of a tunnel rate extraction method using single-frequency pulse spectroscopy
 4. Development of a model for the charge transition curvature
 5. Presentation of a preliminary study on commercial devices based on the split accumulation gate structure
- Favorable comparison
of those 3 criterias
with litterature
results**
- 

Main impact of the thesis

1. Demonstration of the possibility of realization of performant quantum dots with a single gate layer
2. Description of a parameter for performance comparison between different architectures
3. Description of an alternative tunnel rate control method with the reservoir accumulation gate
4. Modelization of the charge transition curvature phenomenon, useful for simulations and machine learning algorithm training for automatic quantum dot initialization
5. Demonstration of the split accumulation gate structure potential for industrial realization of quantum dot processors

Thank you

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